

Monday Morning, October 22, 2018

Nanometer-scale Science and Technology Division

Room 102B - Session NS+2D+AN+EM+MN+MP+PC+RM-MoM

IoT Session: Nanostructured Devices and Sensors

Moderators: David Czaplewski, Argonne National Laboratory, Liya Yu, NIST Center for Nanoscale Science and Technology

8:20am **NS+2D+AN+EM+MN+MP+PC+RM-MoM1 Integrating Nanodiamonds with Augmented Artificial Intelligence and Digital Health to Optimize Combination Therapy, Dean Ho, UCLA** **INVITED**
Dean Ho, Ph.D.

Nanodiamonds have emerged as promising candidates for clinical drug delivery due to their ability to carry a wide range of candidate therapies, unique surface properties, and biological tolerability. This lecture will highlight our recent clinical trial to validate a nanodiamond-embedded biomaterial for root canal therapy indications [1]. We will discuss the broad spectrum of efficacy, safety, characterization, and other studies that bridged in vitro with preclinical and downstream in-human studies. This lecture will also discuss upcoming clinical nanodiamond-based drug carrier studies, as well as our work in augmented artificial intelligence (AI) to develop globally optimized nanodiamond-modified therapy. Pairing nanodiamond platforms with augmented AI will lead to major advances in drug development and markedly improve response rates and treatment outcomes for a broad spectrum of disorders. Our recent clinical trials using these powerful combination therapy optimization technologies and digital health platforms to scale their implementation to usher in a new era of nanomedicine-based treatment will also be discussed [2].

1. Lee et al., Proceedings of the National Academy of Sciences, 2017

2. Zarrinpar et al., Science Translational Medicine, 2016

9:00am **NS+2D+AN+EM+MN+MP+PC+RM-MoM3 Morphology-Controlled Large-Scale Tin Oxide Nanostructures for Highly Sensitive Room Temperature Gas Sensor, Amrit Sharma, Norfolk State University**

Highly sensitive large-scale tin oxide (SnO₂) nanostructures were grown on a glass substrate by vapor-liquid-solid (VLS) process using a mixture of anhydrous tin (II) chloride (SnCl₂) and zinc chloride (ZnCl₂) powders. We demonstrate a new kind of single cell vapor deposition system to precisely control nanostructural morphology by changing the weight ratio of SnCl₂ and ZnCl₂ and growth temperature. The morphology and structural property of as-grown nanostructures were characterized using scanning electron microscopy (SEM) and X-ray diffraction (XRD). The SEM images revealed that the SnO₂ nanostructures with different densities, sizes, and shapes can be achieved by adjusting the weight ratio of SnCl₂ and ZnCl₂. SnO₂ nanostructures with diameter ~20 nm and length ~100 nm showed ~85% sensitivity and 53 seconds of response time, whereas the nanorods with diameter ~100 nm and length ~1mm showed ~50% sensitivity with 198 seconds response time. The nanostructured material with small size and shape showed better sensitivity on sensing at room temperature compared to previously reported SnO₂ based sensors.

9:20am **NS+2D+AN+EM+MN+MP+PC+RM-MoM4 Improving the Localized Surface Plasmonic Resonance Sensing Properties by Composite Metal/Dielectric Mixtures, Steven Larson¹, Y. Zhao, University of Georgia**

Localized surface plasmon resonance (LSPR)-based sensors, whose resonance absorbance wavelength responds to the change in the local dielectric environment have attracted great attention and have been widely studied over the past decade. These sensors are traditionally improved by modifying the shape, size, and gap in the plasmonic nanostructure of the sensor. The sensitivity can also be tuned by the dielectric constant of the plasmonic material, such as noble metal alloys, but the improvements are not significant. Here we show that using a metal-dielectric composite, one can significantly improve the sensitivity of a LSPR sensor. Regular nanotriangle pattern samples composed of a mixture of Ag and MgF₂ with different composition ratios are prepared by combining nanosphere lithography and electron beam co-deposition. The plasmon resonance of these composite nanostructures at high Ag composition (C_{Ag}) are shown to redshift with C_{Ag} until a composition threshold (C_{Ag} ≤ 90%) is met, where the resonance wavelength is nearly constant, slightly blue shifting. Multiple morphological and compositional characterization techniques are used to confirm that the shifts in the

plasmonic properties are due to the change in composition and not a change in the morphology. The resulting LSPR sensor at C_{Ag} = 90 at.% can achieve a sensitivity of 696 RIU/nm, as compared to 312 RIU/nm for the same nanotriangle with pure Ag. This significantly improved sensitivity is due to the modified dispersion relationship of the dielectric constant by the composite and will play an important role in future plasmonic material design and applications.

9:40am **NS+2D+AN+EM+MN+MP+PC+RM-MoM5 Improving the Selectivity of Tin (IV) Oxide Paper Based Gas Sensors with Plasma Surface Modification, Kimberly Hiyoto, E.R. Fisher, Colorado State University**

Metal oxide nanomaterials are desirable for solid-state gas sensors because of their ability to detect a wide variety of gases through changes in resistance resulting from gas-surface interactions. When optimizing these sensors, the supporting substrate is rarely considered, resulting in devices that are often brittle and have a fixed amount of nanomaterial that can be exposed to target analytes. Recent work using paper as the supporting substrate yields more affordable sensors that are flexible, allowing for a more robust device. Furthermore, the porous morphology of the paper also provides a larger surface area to attach metal oxides when compared to a traditional flat substrate of the same dimensions. Another limitation of these metal oxide sensors is inherent in the detection method. The lack of selectivity and required operating temperature of ≥300 °C limits the widespread use of metal oxide sensors. Dopants or the addition of a filter in the device design are typical approaches to address these problems; however, this increases fabrication complexity and cost. Plasma processing is a promising strategy to address these issues because it maintains desirable bulk properties but modifies the surface of the material to enhance gas sensor performance.

Here, we describe the Ar/O₂ plasma modification of paper based, tin (IV) oxide (SnO₂) nanoparticle devices as a function of applied rf power and precursor pressure. After plasma modification, the paper-based sensors exhibited improved response to carbon dioxide, ethanol, and benzene when compared to the untreated material on a more traditional substrate, zirconium dioxide. Additionally, sensor response to a target gas changed depending on the plasma modification parameters used, indicating the selectivity of these SnO₂ sensors can be easily tailored via plasma processing. Response and recovery studies of both the treated and untreated sensors will be discussed to demonstrate the dynamic behavior of these devices to the target gases as another measure of gas sensor performance and durability. Along with sensing behavior, optical emission spectroscopy and X-ray photoelectron spectroscopy provide insight into how the plasma modified the material, ultimately elucidating the relationship between material surface chemistry and sensor selectivity. Finally, preliminary work using this same fabrication process with another type of metal oxide gas sensor will be discussed to demonstrate the applicability of this method for other types of materials. Ultimately, these data work toward improved understanding of the gas sensing mechanism to design better performing gas sensors.

10:00am **NS+2D+AN+EM+MN+MP+PC+RM-MoM6 TiN@Si₃N₄ Core-shell Heterostructures as Nanoantennas for Photocatalytic Reforming of Methanol, Alejandro Alvarez Barragan, L. Mangolini, University of California, Riverside**

The light-harvesting capacity of plasmonic nanoparticles has recently garnered attention in the synthesis of nanoantennas for photocatalysis. Aluminum, gold, and silver have been used to successfully drive hydrogen dissociation and CO oxidation reactions by injecting hot electrons into chemically active catalysts—such as platinum and palladium—adsorbed to their surface. However, the low response of aluminum at visible-near infrared (vis-NIR) wavelengths, the high cost of silver and gold, and the low thermal stability of these three metals, inspire the quest for alternative plasmonic materials that could potentially expand the field towards more ambitious and cost-effective applications. Titanium nitride (TiN) is a conductive ceramic with high hardness and bulk melting point (2930 °C). Its plasmon resonance located in the vis-NIR region, low cost relative to gold and silver, and well-understood properties as a thin film in the semiconductor industry, make it a strong alternative to mainstream plasmonic metals. The present work encompasses a comprehensive study of the oxidation kinetics of TiN particles at the nanoscale and an exploration of its role as nanoantennas for light-induced methanol reformation. TiN particles are synthesized via a scalable, modular, non-thermal plasma method. Titanium and nitrogen precursors are transported into a RF frequency plasma where TiN particles nucleate and grow. The high surface area and nitrogen deficiency of the particles facilitate the

¹ NSTD Student Award Finalist

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oxidation of the material and weaken its plasmonic response. The introduction of a secondary reactor with an input of SiH₄ as precursor gas leads to the formation of a Si₃N₄ coating. STEM and XPS analyses show that Si₃N₄ acts as a diffusion barrier, dramatically reducing the oxidation of the ~8 nm TiN particles. UV-vis-NIR spectrophotometry data show that the core-shell heterostructures experience a substantial blue-shift of the plasmon peak and an increase in intensity compared to the bare TiN. Platinum nanoparticles were subsequently deposited on the TiN@Si₃N₄ by photo-induced reduction of an aqueous solution of chloroplatinic acid. After rinsing and centrifuging, the Pt/TiN@Si₃N₄ heterostructures were diluted in a 50:50 water/methanol solution. Upon photoexcitation via white light illumination, hydrogen generation was readily detected by gas chromatography. This work also highlights the wide range of applications available for light-induced processes, ranging from materials processing (deposition of Pt particles) to photocatalysis (methanol reforming). It also strengthens the case for alternative plasmonic materials in a field dominated by precious metals.

10:40am **NS+2D+AN+EM+MN+MP+PC+RM-MoM8 Nanostructured Sensor and Device Applications of Infiltrated Zinc Oxide**, *Leonidas Ocola*, Argonne National Laboratory; *Y. Wang, J. Chen*, University of Wisconsin-Milwaukee; *P. Blaisdell-Pijuan*, California State University-Fullerton; *R. Divan*, Argonne National Laboratory **INVITED**

With the increased portfolio of materials deposited using atomic layer deposition (ALD) there has been an increased interest in infiltrated metal oxides such as zinc oxide for novel applications. We find that ZnO metal oxide ALD infiltration can be useful for nanoscale resolution imaging of biological samples and to fabricate novel UV and gas nanosensors with high sensitivity. The ALD infiltration utilizes similar concepts of the ALD coating process with the significant difference in process exposure times, pressure, and purpose. The purpose is to allow the precursor gases infiltrate a porous media (such as a dry biological sample or a photoresist polymer) and allow the reaction to occur inside the material matrix.

In terms of device fabrication we use SU8 as a negative resist that allows for localization of the infiltration process. We have used this property to make a device that is UV sensitive, and that is sensitive to ppm concentrations of gases by using infiltrated zinc oxide. The large bandgap and semiconductor properties of ZnO allow for a visible-blind ultra violet light sensor. We used a standard UV flashlight that emits at 408 nm as the UV source. We also tested the same device for sensing gases like nitrous oxide and formaldehyde. We show that the device can detect these gases with concentrations of 5 ppm. The change in current for such low concentrations was measured to be between 25% and 35%.

With the purpose of investigating quantum applications of infiltrated ZnO, we also have characterized the growth of ZnO in PS-b-PMMA block copolymers (BCP) of spherical and cylindrical sub-20 nm morphologies and studied how the photoluminescence of these nanostructures varies per its seed layer. We report blue-shifted photoemission at 335nm (3.70eV), suggesting quantum confinement effects. Samples of ZnO prepared with an alumina seed layer showed additional defect state photoemission at 470nm and 520nm for spherical and cylindrical BCP morphologies, respectively. Defect photoemission was not observed in samples prepared without a seed layer. No Raman peaks were observed for any samples with less than four cycles of ZnO, implying the absence of phonons and the functionality of these ZnO nanostructures as isolated emitters. To that effect we have demonstrated a fabrication path to isolate single infiltrated cylinders, paving the way for further studies of optical properties of individual 20 nm ZnO nanostructures.

- Use of the Center for Nanoscale Materials an Office of Science user facility, was supported by the U.S. Department of Energy, Office of Science, Office of Basic Energy Sciences, under Contract No. DE-AC02-06CH11357.

11:20am **NS+2D+AN+EM+MN+MP+PC+RM-MoM10 Templates for the Investigation of Size-Selected Nanocluster Networks**, *Patrick Edwards, V.V. Kresin*, University of Southern California

The study of metal nanoclusters has revealed quantum nanoscale effects unique to the fully size-resolved regime. A highly notable example is electronic shell structure, akin to that in atoms and nuclei, which arises when confined conduction electrons organize into discrete energy levels. One consequence is the possibility of dramatic enhancement in electron Cooper pairing. Recent research from our group has provided evidence of this enhancement in certain free Al nanoclusters, with the electronic transition taking place at a temperature two orders of magnitude above that of bulk aluminum. We now aim to take advantage of this phenomenon by exploring the pairing transition in size-selected nanoclusters soft-landed

on an appropriate substrate. Of particular interest are graphene and nanotube device architectures which provide unique templates for organizing nanocluster arrays. For example, a network of such superconducting nanoislands may induce superconductivity in graphene even at low coverages. Theory also predicts that an array of nanoclusters will not only support, but even enhance the Josephson current by 2-3 orders of magnitude. Carbon allotropes offer two distinct advantages for our system. First, the weak out-of-plane bonding provides a surface with less potential to disturb the structure of the soft-landed nanoclusters. Second, the tunability of graphene and carbon nanotube-based field effect transistors offers a versatile probe of nanocluster properties. We are also investigating the use of biological nanowires (bacterial flagella) as potential scaffolds upon which to deposit such nanocluster networks. These abundant and naturally occurring nanowires could serve as low cost and highly reproducible alternatives to the more common metallic or semiconductor templates.

Research supported by the Army Research Office (W911NF-17-1-0154).

11:40am **NS+2D+AN+EM+MN+MP+PC+RM-MoM11 High Performance Detection for X-ray and g -ray with MAPbX₃ Perovskite Single Crystals**, *X. Wang, Z. Zhu, Q. Li, J. Wu, X. Zhang, B. Wang, Wei Lei*, Southeast University
Recently, organometallic lead trihalide perovskites have emerged as a new generation of opto-electronic materials. However, the high performance detection for x-ray and gamma-ray with MAPbX₃ is still a big challenge. For x-ray and gamma-ray detections, the detectors should have high sensitivity. If the photon counting method is adopted, the high energy resolution and high time resolution are also required. In this work, the large area MAPbBr₃ single crystal has been fabricated with a facile methodology. Due to the quite thick active material and large carrier mobility, the x-ray photons and gamma-ray photons can be absorbed with high efficiency. The photo generated electrons and holes can also be collected effectively with the large electric field. To decrease the dark current in the detection, a novel photo-diode structure is proposed here. In crystallization process of MAPbI₃ single crystal, the p-n junction can be formed with doping of selenium atoms into MAPbI₃ single crystal.

With various temperature method, the 30mm×30mm×7mm MAPbBr₃ single perovskite crystal is fabricated. As the experimental results shown, almost all of the 100 keV x-ray photons are absorbed when the MAPbBr₃ SPC is 7mm thick. The detection sensitivity is as high as 305 μC Gy_{air}⁻¹cm⁻² when the anode voltage of x-ray tube is 30 kV .

To reduce the dark current in the detection, two type of photo diode structures have been proposed here. Firstly, a photo diode with structure of Au/TPD/MAPbBr₃ PSC/C₆₀/PCBM/Ag has been fabricated with spin coating and sputtering methods. Although the dark current density can be reduced to 20 nA/cm² with -30V bias voltage, the temporal response time is nearly 50 μs due to the defects on the interfaces between PSC and carriers transport layers. Then, by doping selenium (Se) in MAPbI₃ perovskite single crystals (DPC) crystallization process, low dark current p-n junctions were fabricated without any organic layers. This photodiodes gives the high detection sensitivity as 21000 mC Gy_{air}⁻¹cm⁻² and 41 mC Gy_{air}⁻¹cm⁻² for 60 keV x-ray and 1.33 MeV gamma-ray respectively. In this photodiode, the transition time becomes shorter under higher electric field, and the carrier lifetime also becomes shorter due to the dopant of Se atoms. Finally, the temporal response time is measured as 3 μs by experiments. The FWHM width of energy spectrum is decreased to 3.2%@1330 keV.

Nanometer-scale Science and Technology Division Room 102B - Session NS+AN+EM+MN+MP+RM-TuM

Nanophotonics, Plasmonics, and Metamaterials

Moderators: Alokik Kanwal, NIST Center for Nanoscale Science and Technology, Nikolai Klimov, National Institute of Standards and Technology

8:00am **NS+AN+EM+MN+MP+RM-TuM1 Parametric Nonlinear Interactions in Nanofabricated Silicon-based Photonics, Amy Foster**, Johns Hopkins University **INVITED**

High optical confinement waveguides on integrated platforms enable nonlinear optical interactions with low power levels. The third-order nonlinear susceptibility, a modification of a material's permittivity due to an applied optical field, exists in all materials, and is an intensity-dependent process leading to third-order parametric effects. Harnessing the high optical intensities enabled by high confinement waveguides allows standard semiconductor materials to become power-efficient parametric nonlinear optical devices that can operate with powers in the mW range. The optical confinement of a waveguide also enables control over the waveguide's dispersion, allowing for phase-matching of the parametric processes thereby improving its operating bandwidth. Using standard nanofabrication techniques, integrated photonic devices can be tailored in both geometry at the nanoscale, and in magnitude of their third-order susceptibility through modification of their material properties. In this talk, we will discuss a variety of parametric nonlinear optical demonstrations in silicon-based waveguides including optical parametric amplification and oscillation, phase-sensitive amplification, and frequency conversion and comb generation. Furthermore, we will discuss these devices for a variety of applications including optical signal processing, spectroscopy, and security.

8:40am **NS+AN+EM+MN+MP+RM-TuM3 Ultrafast Optical Pulse Shaping using Dielectric Metasurfaces, Amit Agrawal, S. Divitt, W. Zhu, C. Zhang, H.J. Lezec**, NIST Center for Nanoscale Science and Technology **INVITED**

Since the invention of femtosecond pulsed lasers, the field of ultrafast optical science and technology has seen significant progress in the generation and characterization of ultrashort optical pulses. Complimentary to development in generation and characterization techniques, arbitrary temporal shaping of optical pulses has become an integral part of the field. Fourier-transform pulse shaping is the most widely adopted approach that entails parallel modulation of spatially separated frequency components to achieve the desired pulse shape. Recently, dielectric metasurfaces have emerged as a powerful technology for arbitrary control over the amplitude, phase, or polarization of light in a single, compact optical element. Here, we experimentally demonstrate shaping of sub-10 fsec ultrafast optical pulses using a centimeter-scale silicon metasurface acting as both amplitude and phase modulation mask. The deep-subwavelength silicon nanostructures, positioned with nanometer precision, are individually optimized to provide accurate amplitude and phase modulations to each frequency component. Masks of this type offer a lower cost, larger size, higher resolution, high diffraction efficiency, high damage threshold method for controlling ultrafast pulses.

9:20am **NS+AN+EM+MN+MP+RM-TuM5 Single-Particle Nanophotonics and Materials Investigations with Optical Microresonator Spectrometers, Erik Horak**, University of Wisconsin - Madison; *K.D. Heylman, K.A. Knapper, M.T. Rea, F. Pan, L.T. Hogan, R.H. Goldsmith*, University of Wisconsin-Madison **INVITED**

Optical microresonators have achieved impressive sensitivities in a range of experimental modalities. We leverage the exquisite sensitivity of microresonators to enable highly sensitive spectroscopic characterization of objects on the surface of the resonator. In this way, not only can single particles be detected and identified, but fundamental properties of interrogated systems can be studied, opening a path to mechanistic studies and label-free chemical identification.

Our photothermal-based technique employs a two-beam geometry. A fiber-coupled (probe) beam records the whispering-gallery mode (WGM) resonance wavelength via evanescent coupling through a tapered fiber, while a second free-space (pump) beam heats absorbing particles or molecules on the surface of the microresonator, shifting the WGM resonance. In essence we use the microresonator as a nearfield thermometer to measure dissipated heat upon optical excitation. To circumvent the photothermal background of the popular SiO₂ on Si toroidal resonators, we have developed an all-SiO₂ microtoroidal resonator,

unlocking visible wavelengths to interrogation. We further employed a double-modulation technique through simultaneous Pound-Drever-Hall locking of the probe beam and amplitude modulation of the pump beam to reach sub-100 Hz or single attometer resonance shift resolution. This corresponds to signals much smaller than that predicted from a single-molecule, and thus represents an avenue toward single-molecule absorption spectroscopy.

We demonstrate this technique by examining gold nanorods (AuNR), which validate our experimental setup with near-diffraction limited photothermal maps, Lorentzian absorption spectra with stochastic center wavelengths, and single dipole polarization dependences. Further, AuNRs in close proximity to microresonator WGMs display signatures of photonic-plasmonic interactions, a forest of Fano resonances decorating the plasmonic absorption feature. This platform offers a facile methodology to study these complex interactions, with thermal annealing of the AuNRs producing highly controllable tuning of Fano resonances. Applying our platform to conductive polymers (CP), we have begun to understand the fundamental properties that enable the high conductivity from a bottom-up nanoscale perspective. We examine the interplay between homogeneous and heterogeneous broadening, measure the long-range ordering, and determine relative surface orientation of CPs. These examples firmly demonstrate the utility of our platform to go beyond sensing allowing exploration of novel characteristics in complex systems and potentially the observation of chemical and biochemical dynamics.

11:00am **NS+AN+EM+MN+MP+RM-TuM10 Optomechanical Interactions for Metrology and Signal Processing, Karen Grutter**, The Laboratory for Physical Sciences **INVITED**

Imprinting radio-frequency (RF) signals on optical carriers has a broad range of applications from metrology to communication and has been accomplished in bulk components using a variety of techniques. Achieving this functionality on a chip could broaden the potential application space, but the bulk frequency generation methods do not translate directly to the nanoscale. A number of methods have been proposed for on-chip frequency generation, including various sources of electro-optic modulation, comb generation via material nonlinearities in microresonators, and optomechanical/opto-acoustic interactions. In this talk, we will discuss the features of these sources, with particular focus on optomechanical interactions.

One potential phenomenon enabling opto-acoustic frequency generation is stimulated Brillouin scattering (SBS), which is essentially an interaction between propagating phonons and photons. This effect has been demonstrated in optical fibers, and recent results in on-chip waveguides show promise. One of the challenges with SBS on chip is that gain is dependent on long interaction lengths.

This interaction can be enhanced by moving to a different domain of phonon/photon interaction: cavity optomechanics. In an optomechanical cavity, the characteristics of the generated frequency are dependent on the mechanical eigenmode. We will demonstrate the relationship between mechanical quality factor and phase noise in ring optomechanical oscillators.

The optomechanical interaction can be optimized beyond that of ring resonators by further confining optical and mechanical modes using photonic and phononic crystals. We have designed and fabricated Si₃N₄ nanobeam optomechanical crystals with ~4 GHz mechanical breathing modes. The increased optomechanical coupling of these nanobeams confers high sensitivity to displacement, which could be exploited for various metrology applications, which we will discuss.

Further enhancement of the optomechanical coupling can be achieved by modifying the optomechanical crystal geometry to support an optical slot mode. We have designed and fabricated ~3 GHz-frequency slot-mode optomechanical crystals in Si₃N₄. In addition to increasing the optomechanical coupling compared to the single-nanobeam device, this structure has increased versatility, enabling interaction with other stimuli and modalities. We have integrated NEMS actuators with a slot-mode optomechanical crystal, and used these actuators to tune the optical mode and lock it to an external, fixed laser wavelength. This increases the practicality of this device, enabling longer-term measurements and stabler frequency sources.

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11:40am **NS+AN+EM+MN+MP+RM-TuM12 Cold-atom based Sensors and Standards**, *Stephen Eckel, D.S. Barker, J.A. Fedchak, N.N. Klimov, E. Norrgard, J. Scherschligt*, National Institute of Standards and Technology

INVITED

In this talk, I will describe our recent efforts to merge nanophotonics, ultra-high vacuum, and atomic physics together to build a new generation of cold atom sensors and standards. In particular, I will focus on our recent realization of a single-beam system for cooling lithium atoms, an atomic species recently identified as an excellent candidate for a primary vacuum standard. Our system uses a triangular-shaped nanofabricated diffraction grating to produce the necessary beams for a magneto-optical trap that cools and slows the atoms. Unlike systems that use rubidium or cesium, which can be loaded from a vapor, lithium introduces additional complications because it must be produced from a thermal source requiring loading of the magneto-optical trap from behind the chip. Finally, I will conclude by talking about other trap geometries that we are pursuing, how they benefit vacuum and inertial sensors, and what the synergy of integrated nanophotonics, high-vacuum and atomic physics might be able to bring.

Electronic Materials and Photonics Division Room 101A - Session EM+2D+AN+MI+MP+NS-TuA

Solar/Energy Harvesting and Quantum Materials and Applications

Moderators: Yohannes Abate, Georgia State University, Nicholas Strandwitz, Lehigh University

2:20pm **EM+2D+AN+MI+MP+NS-TuA1 Plasmonic Metasurface Electrodes for Excitonic Solar Cells.**, *Deirdre O'Carroll*, Rutgers, the State University of New Jersey **INVITED**

Excitonic organic solar cell technologies, while not currently competitive with inorganic-semiconductor analogues, can exhibit very small device embodied energies (due to comparatively low temperature and low energy-use fabrication processes), which is of interest for minimizing overall device cost and energy-payback time. To improve energy conversion efficiency in thin-film excitonic organic solar cells, light management using nanophotonic structures is necessary. Here, our recent work on improving light trapping in deeply-subwavelength excitonic organic semiconductor films using plasmonic metasurfaces will be presented. Numerous exciton-metasurface interaction phenomena, such as absorption-induced scattering, exciton-plasmon coupling and morphology-dependent surface plasmon light-trapping are observed to give rise to improved light trapping at different regions of the solar spectrum. Additionally, an approach to achieve the theoretical limits to the efficiency of excitonic organic photovoltaics (~22%) will be proposed that involves control of radiative recombination rate, and optimization of both photoluminescence quantum efficiency and photon recycling in organic semiconductor thin-films.

3:00pm **EM+2D+AN+MI+MP+NS-TuA3 Photoemission Electron Microscopy as a New Tool to Study the Electronic Properties of an Inhomogeneous Semiconductor for Photovoltaics**, *M. Berg*, Sandia National Laboratories; *J. Kephart*, *A. Munshi*, *W.S. Sampath*, Colorado State University; *Taisuke Ohta*, *C. Chan*, Sandia National Laboratories

The energy positions of the valence and conduction electronic states with respect to the vacuum level are essential parameters to evaluate how the band gaps of semiconductors or Fermi-levels of metals line up with respect to each other. Such electronic structures of materials can be determined using photoemission spectroscopy (PES). PES measurements, however, remain challenging for inhomogeneous materials with nano- to micrometer lateral dimensions due to its mesoscopic probing area, typically no less than several microns. Photoemission electron microscopy (PEEM) is a cathode lens electron microscopy technique that combines photoemission imaging with spectroscopic modes of operation to provide PES spectra from areas less than one micron in size. Here, we present PEEM studies of the electronic structure of polycrystalline cadmium telluride (CdTe) thin films, a test case to examine the applicability of this new microscopic approach to photovoltaic materials. Post-deposition CdCl₂ treatment of CdTe is known to increase photovoltaic efficiency. However, the precise chemical, structural, and electronic changes that underpin this improvement are still debated. In this study, PEEM was used to spatially map the vacuum level and ionization energy of CdTe films, enabling the identification of electronic structure variations between grains and grain boundaries. *In vacuo* preparation and inert environment transfer of oxide-free CdTe surfaces isolated the separate effects of CdCl₂ treatment and ambient oxygen exposure. Qualitatively, grain boundaries displayed lower work function and downward band bending relative to grain interiors, but only after air exposure of CdCl₂-treated CdTe. This study highlights the importance of probing the spatially varying electronic structure, elucidating the concurrent impacts of processing steps (CdCl₂ treatment and oxygen exposure) to develop a comprehensive picture of local electronic structure in an inhomogeneous semiconductor.

The PEEM work was performed at the Center for Integrated Nanotechnologies, an Office of Science User Facility (DE-AC04-94AL85000). M. B. & C. C. were supported by a U.S. DOE-EERE SunShot BRIDGE award (DE-FOA-0000654 CPS25859). T. O. was supported by the CINT user program and Sandia LDRD. Sandia National Laboratories is a multi-mission laboratory managed and operated by National Technology and Engineering Solutions of Sandia, LLC., a wholly owned subsidiary of Honeywell International, Inc., for the U.S. Department of Energy's National Nuclear Security Administration under contract DE-NA0003525. The views

expressed in the article do not necessarily represent the views of the US DOE or the US Government.

3:20pm **EM+2D+AN+MI+MP+NS-TuA4 Modification of Bandgap for Lead-Free Double Perovskite Cs₂AgInCl₆ with Bi Doping**, *Hassan Siddique*, *H. Da*, *X.Q. Wang*, *R.C. Dai*, *Z.P. Wang*, *Z.J. Ding*, *Z.M. Zhang*, University of Science and Technology of China

Lead halide perovskites have the excellent luminescent properties but exist some vital disadvantages such as instability and Pb toxicity. Lead-free double perovskites draw attention due to a possible candidate for environment-friendly materials. Direct bandgap lead-free halide of Cs₂AgInCl₆ is one of them. [1] In this work Bi doping Cs₂AgInCl₆ (CAIC) was successfully prepared. Bi dopant above 15% CAIC can restrict the parity forbidden transition responding to sub absorption peak around 600 nm.[2] On the other hand, the intensity of photoluminescence enhances with the increasing Bi dopant and touches the maximum around 30% doping, then gradually loses its intensity with further doping due to the mechanism of the concentration quenching at room temperature. Bi doping in CAIC can also modify the band gap. The absorption spectra indicate that the band gap reduces from 3.10eV without Bi doping to 2.68eV for Cs₂AgIn_{0.30}Bi_{0.70}Cl₆. PL decay life time reveals the good intrinsic excitonic feature with less defect trappers [3]. Average life time for Cs₂AgIn_{0.70}Bi_{0.30}Cl₆ is 490 ns which is least among all other Cs₂AgIn_(1-x)Bi_xCl₆ doping. Thermogravimetric analysis (TGA) result reveals thermal stability of Cs₂AgIn_{0.30}Bi_{0.70}Cl₆ for the high-temperature 506°C. The Bi doping can decrease the band gap, restrict defect states, enhance PL and improve stability; these good performances make Cs₂AgIn_(1-x)Bi_xCl₆ more suitable for optoelectronic properties.

4:20pm **EM+2D+AN+MI+MP+NS-TuA7 Optimized (Quantum) Photonics**, *Jelena Vuckovic*, Stanford University **INVITED**

Photonics has numerous applications ranging from optical interconnects, classical and quantum computing, to sensing (such as LIDAR and AR), and imaging. However, the state of the art photonics is bulky, inefficient, sensitive to environment, lossy, and its performance is severely degraded in real-world environment as opposed to ideal laboratory conditions, which has prevented from using it in many practical applications. Therefore, it is clear that new approaches for implementing photonics are crucial.

We have recently developed a computational approach to inverse-design photonics based on desired performance, with fabrication constraints and structure robustness incorporated in design process [1,2]. Our approach performs physics guided search through the full parameter space until the optimal solution is reached. Resulting device designs are non-intuitive (see Figure), but are fabricable using standard techniques, resistant to temperature variations of hundreds of degrees, typical fabrication errors, and they outperform state of the art counterparts by many orders of magnitude in footprint, efficiency and stability. This is completely different from conventional approach to design photonics, which is almost always performed by brute-force or intuition-guided tuning of a few parameters of known structures, until satisfactory performance is achieved, and which almost always leads to sub-optimal designs.

Apart from integrated photonics, our approach is also applicable to any other optical and quantum optical devices and systems. In recent years, color centers in diamond and silicon carbide (SiC) have emerged as a possible platform for implementation of quantum circuits [3,4]. We demonstrate how such quantum hardware can also be optimized to be robust, efficient, and scalable.

References

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- [2] L. Su et al, *ACS Photonics* ASAP (2018)
- [3] J.L. Zhang et al, *Nano Letters* 18 (2), 1360-1365 (2018)
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5:00pm **EM+2D+AN+MI+MP+NS-TuA9 Optical Properties of Single Silicon Vacancies in 4H-SiC**, *H.B. Banks*, National Research Council Postdoc residing at the Naval Research Laboratory; *O. Soykal*, Sotera Defense Solutions, Inc, residing at the Naval Research Laboratory; *S.P. Pavunny*, *R.L. Myers-Ward*, *D.K. Gaskill*, *Samuel Carter*, U.S. Naval Research Laboratory
Defects in wide bandgap materials have generated substantial interest as promising systems for quantum information and quantum sensing due to bright, stable optical emission that is often coupled to long-lived spin states. One promising defect system is the silicon monovacancy in SiC (V_{Si}), which has a spin-3/2 ground state that can be optically polarized and maintain long spin coherence times even at room temperature. SiC is an attractive material in terms of mature growth and fabrication technology

and also has a low natural abundance of nuclear spins, which reduces spin dephasing. While significant work has been performed to study the spin properties of V_{Si} for ensembles and even single defects, the optical properties and their connection to the spin system are less developed. Here we report on high resolution optical spectroscopy of single V_{Si} defects, specifically V2 defects, at low temperatures. Using laser excitation spectroscopy, the zero phonon line (ZPL) transitions corresponding to the $m_s = \pm 1/2$ and $m_s = \pm 3/2$ spin states are resolved, with a linewidth down to 70 MHz and a splitting of 1 GHz. While there is significant variation in the transition energies from one defect to another, the splitting of these lines is very uniform. We also find that emission from the V2 defect under resonant excitation of these lines rapidly decays on two very different timescales. Slow decay on a 10 ms timescale is attributed to photoionization of V_{Si} and can be prevented by periodically exciting the defect with a second laser at 745 nm. Fast decay on a μs or shorter time scale occurs due to a combination of intersystem crossing and spin polarization of the ground state. A significant difference in the decay rates of the two transitions is observed, which gives rise to spin-dependent photoluminescence intensity and non-resonant optical spin polarization. These results further our understanding of the connection between the optical and spin properties of this defect system that are necessary to optically control and readout the spin system as well as to develop a spin-photon quantum interface.

5:20pm **EM+2D+AN+MI+MP+NS-TuA10 Photoluminescence Studies on Patterned Silicon Vacancy Defects in Li Ion Implanted 4H-SiC for Scalable Quantum Device Applications**, *Shojan Pavunny*, U. S. Naval Research Laboratory; *S.G. Carter, H.B. Banks, R.L. Myers-Ward, P. Klein*, U.S. Naval Research Laboratory; *E.S. Bielejec*, Sandia National Laboratories; *M.T. DeJarlid, A.S. Bracker, E.R. Glaser, D.K. Gaskill*, U.S. Naval Research Laboratory

Recently, silicon vacancy defect centers (V_{Si}) in the CMOS compatible wide bandgap semiconductor SiC hexagonal polytypes have drawn great research interest for future applications in scalable quantum information and quantum sensing mainly due to their high electronic spin ($S = 3/2$) with a long coherence time at room temperature. Realization of future densely integrated quantum devices will greatly benefit from the ability to deterministically induce the desired V_{Si} density at the optimal location in the three-dimensional solid-state matrix with nanometer accuracy and excellent optical properties. With this motivation, we demonstrate targeted formation of arrays of V_{Si} ensembles as well as single defects in high-quality 4H-SiC epilayers by a direct, maskless focused ion beam implantation technique with a designed lateral separation of $\sim 5 \mu m$ and a $\sim 25 nm$ spot size. We have carried out high-resolution optical spectroscopy studies (ELC and E||c) on these arrays, in which lithium ions are implanted at doses varying from $10^{12} - 10^{15} Li/cm^2$ at a fixed energy of 100 keV to a depth of $\sim 400 nm$ from the surface. Photoluminescence intensity and defect conversion yield with dose, photostability, fluorescence saturation, and $V_1:V_1'$ intensity evolutions with temperature and excitation power were investigated. Results obtained from temperature dependent photoluminescence studies can provide key insights in the design and fabrication of scalable and reproducible three dimensional SiC quantum hybrid devices including photonic crystal cavities.

5:40pm **EM+2D+AN+MI+MP+NS-TuA11 Processing of Cavities in SiC Material for Quantum Technologies**, *Rachael Myers-Ward, K. Hobart, K.M. Daniels, A.J. Giles, M.J. Tadjer, L.E. Luna, F.J. Kub, S.P. Pavunny, S.G. Carter, H.B. Banks, E.R. Glaser*, U.S. Naval Research Laboratory; *P.B. Klein, Sotera Defense Solutions; K. Qiao, Y. Kim, J. Kim*, Massachusetts Institute of Technology; *D.K. Gaskill*, U.S. Naval Research Laboratory

Silicon carbide is a material of interest for quantum computing and sensing applications owing to deep point defect centers with long spin coherence times (which characterizes the lifetime of the qubit), specifically the V_{Si} [1], divacancies [2] and nitrogen-vacancy centers [3]. These spin qubits have been isolated and coherently controlled, where V_{Si} have T_2 coherence times up to 100 μs [4] and divacancies to 1 ms [2], making these two defects of most interest to date. While the current spin coherence times have been shown to be as long as 1 ms, further improvements are needed to fully realize the potential of SiC for quantum applications. In this work, we create V_{Si} in epitaxial SiC and investigate fabricating the layers into microstructures suitable for using the V_{Si} photoluminescence (PL) emission. We have found 4H-SiC epitaxial layers grown under standard growth conditions and with varying doping densities from 10^{14} to $10^{18} cm^{-3}$ have no measurable V_{Si} present, as determined by confocal PL. To introduce V_{Si} , we used 2 MeV electron irradiation in doses ranging from 0.75 to 75 kGy.

This results in V_{Si} PL ranging from single to ensemble emission within the confocal volume. Hence, we are able to tune the vacancy concentration.

In order to improve the indistinguishable photons from the V_{Si} and/or divacancies for real applications, photonic crystal cavities (PCC) are used to tune the emission energy [4]. Our PCC design consists of a planar array of cylindrical holes approximately 220 nm wide in a slab of SiC, $\sim 300-500 nm$ thin having an area $50 \times 50 \mu m^2$, similar to [4]. To maximize the PCC quality factor, the slab should have a large index of refraction difference on the top and bottom; i.e., an air gap is desired under the slab. To achieve this goal, we have identified four fabrication methods to create the PCC. One of these techniques is to use remote epitaxy as an innovative approach which entails growing epitaxial graphene on a SiC substrate by means of Si sublimation. Silicon carbide is then grown on a monolayer of graphene to the desired film thickness [5]. This thin SiC layer is then transferred, facilitated by the weak van der Waal forces at the graphene/SiC substrate interface, to a substrate more amenable to cavity fabrication. All four fabrication methods will be presented in detail.

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6:00pm **EM+2D+AN+MI+MP+NS-TuA12 Investigation of Localized Electronic structures of PbSe Quantum Dot Superlattice on a Highly Oriented Pyrolytic Graphite (HOPG)**, *Il Jo Kwak, S. Ueda*, University of California at San Diego; *A. Abelson, C. Qian, M. Law*, University of California, Irvine; *A.C. Kummel*, University of California at San Diego

Lead-Chalcogenide quantum dots are of interest due to the facility of adjustment of their electrical and optical properties. Using a colloidal self-assembly technique, extended arrays of nanocrystal QDs superlattices can be generated. The quantum confinement within individual QDs in the superlattice is relaxed and delocalization of wave functions occurs due to coupling of the QDs. In the QD solids, bulk-like electronic bands with a bandwidth of 100~200 meV are expected to form which yield much higher carrier mobility and diffusion length compared to weakly-coupled QDs; however, the electronic properties of such highly ordered QD arrays are not fully understood. The local density of state of a highly ordered monolayer PdSe superlattice was investigated by low temperature scanning tunneling microscopy.

A monolayer of PbSe QDs was prepared using the Langmuir Schaefer deposition technique. First, oleate-capped PbSe QDs dispersed in hexane were drop casted onto diethylene glycol surface. After the hexane was evaporated, a (111) in-plane oriented polycrystalline FCC superlattice was formed on the diethylene glycol surface. NH_4SCN solution was applied onto the oleate-capped PbSe superlattice film. The injection of NH_4SCN initiates the ligand exchange and phase transformation from an FCC to a simple cubic structure superlattice. A monolayer QD superlattice was prepared on a HOPG substrate. Afterward, the HOPG sample was loaded into a commercial UHV scanning tunneling microscopy chamber with a base pressure of $1 \times 10^{-10} torr$. The sample was annealed to remove hydrocarbons and ligands from the surface. The topography of the QDs was observed with a tungsten tip. The STM images were acquired in constant current mode.

STM imaging showed the PbSe QD monolayer had 4-fold symmetry with an average inter QD spacing of 7nm. It is also found the height fluctuation of the QDs was 1nm indicating size variation of the QDs and imperfect crystal structure of the superlattice. Scanning tunneling spectroscopy was performed to investigate the electronic structure of the PdSe QDs using a variable z-mode with an external lock-in amplifier in the bias range of -2 to 2V. Single site STS showed resonant peaks from molecular orbitals of QDs before the ligand exchange process; however, the peaks were not observed after the ligand exchange due to necking between the QDs in the superlattice. In addition, the size of band gap was decreased as increasing the number of nearest neighboring QDs due to necking between QDs. Layer 2 QDs showed more p-type behavior than layer 1 QDs possibly due to the band bending effect at the interface of HOPG and QD superlattice.

Electronic Materials and Photonics Division Room 101A - Session EM+AN+MI+SS-WeM

Surface and Interface Challenges in Electronics and Photonics

Moderators: Andy Antonelli, Nanometrics, Michael Filler, Georgia Institute of Technology

8:00am **EM+AN+MI+SS-WeM1 Few Monolayer Atomic Layer Deposition (ALD) to Engineer New Surfaces and Interfaces, Parag Banerjee, Washington University in St. Louis** **INVITED**

Atomically precise modification of surfaces and interfaces with few monolayer material leads to improved understanding and significant enhancements in properties, performance and reliability of heterogeneous materials and devices. This talk highlights the impact of few monolayer insulators, wide bandgap semiconductors and metals, deposited using atomic layer deposition (ALD) on a variety of surfaces and interfaces with direct relevance to electronic and photonic devices.

The first part of this talk deep dives into the process science of ALD in its early cycles. The nature and structure of few monolayer ALD films is highlighted. In particular, configurational state and entropy of adlayers during every half-cycle of ALD¹ is exploited to exquisitely manipulate nucleation and growth of metallic Ru thin films.²

In the second part of this talk, applied aspects of few monolayer engineering of surfaces and interfaces is discussed. Case studies included are the non-linear optical phenomena on Au-Al₂O₃ and Au-ZnO surfaces,³ high performance photocatalysts for CO₂ photoreduction,⁴ improved optoelectronic responses from surface passivated CuO nanowires⁵ and few monolayer Ta₂O₅ to improve reliability of electrochromic windows.⁶

Regardless of the application, ALD at its ultimate thickness limit holds true potential for surface and interface engineering. The control of this process appears to be remarkably simple and yet, has hidden complexities that continue to push the boundaries of discovery of new materials and concept devices.

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⁵ Sriya Banerjee, Zhengning Gao, Fei Wu, Yoon Myung, and Parag Banerjee, *Under Review* (2018).

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8:40am **EM+AN+MI+SS-WeM3 Lattice-alignment mechanism of SiGe on Sapphire, HyunJung Kim, National Institute of Aerospace; S. Choi, NASA Langley Research Center**

In the conventional heteroepitaxy processes, the deposition of dissimilar materials has been made with the same or similar crystal structure and perfect or nearly matching lattice constants, such as Ge/Si (diamond cubic), InAs/GaAs (zinc-blende), and GaN/Al₂O₃ (hexagonal/trigonal). On the other hand, the super-heteroepitaxy of two semiconductors with dissimilar crystal structures such as SiGe (diamond cubic)/Al₂O₃ (trigonal) is not readily achievable but requires scrupulous manipulation of growth conditions for single crystal formation. Epitaxial growth patterns of SiGe on *r*-plane and *c*-plane of sapphire substrates show 90°-rotated and 60°-rotated twin defects, respectively [1,2].

A team at NASA Langley Research Center developed a technique for super-hetero-epitaxy of single crystal SiGe growth; diamond-cubic structure of SiGe on trigonal structure of the *c*-plane sapphire substrate by a transformed lattice structure under a new lattice-alignment model [2]. Although the growth conditions were effective for the formation of single

crystal film, how the mechanism or physics of single crystal formation of SiGe at the interface of sapphire was not theoretically and experimentally defined with the order of atomic scale level in arrangement. This work presents the interfacial image of SiGe/Al₂O₃ using high-resolution transmission electron microscope (HRTEM) to show the SiGe/Al₂O₃ interfacial bonding for superheteroepitaxy mechanism. The first two atomic layers of the SiGe are Si-rich where Si atoms match with the surface oxygen lattice of the Al₂O₃ substrate. After the Ge composition increases, the monolayer spacing is also increased due largely to the dominance of Ge composition since the lattice constant of Ge is bigger than that of Si. These results highlight the importance of a cleanliness of sapphire substrate, the Si-affinity to oxygen that ties up Si- of SiGe with the oxygen of sapphire, and eventually causing the deformation of SiGe cubic structure for super-heteroepitaxy [3]. From the essential understanding of the SiGe/Al₂O₃ interface mechanism, both low temperature SiGe super-heteroepitaxy and the III-V or II-VI semiconductor epitaxy are possible.

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9:00am **EM+AN+MI+SS-WeM4 An Effort to Resolve Band Offset Anomalies in ZnO/GaN Heterostructures, Monu Mishra¹, A. Gundimeda, V. Vandana, G. Gupta, CSIR-National Physical Laboratory, India**

Gallium Nitride (GaN) and Zinc Oxide (ZnO) are well established wide band gap (WBG) semiconductors facilitating potential application in futuristic energy-efficient opto/micro-electronics technology. Despite of owing the merits of both semiconductors, the understanding of ZnO/GaN heterostructures is still posing challenges. The available reports display anomalies amongst calculated valence band offset (VBO) and defect state of ZnO/GaN interface. The influence of surface and interfacial properties perturbs the electronic structure, localized charge density and defect states at the interface, yet the impact of these properties on VBO requires more scientific attention. Hence, sharp interfaces of ZnO/GaN heterostructures (ZnO thickness = 2, 5 and 8 nm) were fabricated via atomic layer deposition (ALD) of ZnO on MOCVD grown highly crystalline GaN epilayer and further investigated by HR-XPS, UPS and PL spectroscopy. The impact of ZnO thickness on band bending (upwards & downwards), surface/interface dipole strength and defects states (vacancies, interstitials, donor/acceptors etc.) on valence & conduction band offsets (VBO/CBO) were thoroughly analysed. It was observed that the VBO at the interface was reduced via 0.6 eV as the ZnO thickness was increased from 2 nm to 8 nm which was ascribed to interface dipole strength along with dramatic change in localized BB (downwards-flatband-upwards). A type-II band alignment was perceived at all ZnO/GaN interfaces though the nature & contribution of defects states (especially oxygen vacancies and zinc interstitials) varied incommensurately. The defect band spectra revealed a blue shift (~502 eV) which correspond to the conversion of yellow-green emission in ultrathin ZnO/GaN heterostructure (2 nm ZnO) to characteristic green emission in bulk ZnO. The analysis revealed that the thickness of ZnO overlayer in ZnO/GaN heterostructure significantly alters the electronic structure and defect states at the interface and thus the resolution of anomalies in the present analysis would be useful for the fabrication of ZnO/GaN heterostructure based efficient optoelectronic devices.

9:20am **EM+AN+MI+SS-WeM5 Stress Relaxation in the Si-SiO₂ System and its Influence on the Interface Properties, Daniel Kropman, T. Laas, Tallinn University, Estonia; A. Medvids, Riga Technical University, Latvia**

It is known that internal mechanical stresses (IMS) due to the differences in the thermal expansion coefficients between films and substrates and lattice mismatch appear in the Si-SiO₂ system during the process of its formation and that point defects (PD) generation and redistribution could be used to reduce partially the surface stress. However, this process on the atomic scale is still not studied. The goal of the present report is to investigate the stress relaxation mechanism in the Si-SiO₂ system using EPR, IR absorption spectroscopy, scanning electron microscopy (SEM) and samples deflection measurements. PD density and stresses in the Si-SiO₂ system were varied by oxidation condition (temperature, time, cooling rate, ambient) and by Si₃N₄ deposition on SiO₂. Different sign of the thermal expansion coefficient of the SiO₂ and Si₃N₄ on Si allow to modify the IMS at the interface. It has been found that samples deflection decreases or increases simultaneously with EPR signal intensity depending on the oxidation condition (temperature).

¹ National Student Award Finalist

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At oxidation temperature 1100°C the deflection of the samples(h) decreases with the increase of EPR signal intensity (vacancies), while at a oxidation temperature 1200°C EPR signal (I) and deflection increase simultaneously. Those allows to suggest that at lower oxidation temperature PD (vacancies) reduce the tensile IMS in Si, while at higher oxidation temperature compressive IMS created PD in SiO₂ (E' centers). At

an intermediate oxidation temperature tensile stresses in Si and compressive stresses in SiO₂ may be equal and compensate each others. It has been found that at oxidation temperature 1130°C IMS at the Si-SiO₂ interface are lower than at 1100°C and 1200°C. Lower defect density on samples cross-section microphotos obtained by SEM and PD density diminishing in samples oxidized at 1130°C confirmed this suggestion. In

Fig.2 the EPR signal and IR absorption line-width dependence on the oxidation time is shown. It can be seen, that EPR signal and IR absorption line-width at 1100 cm⁻¹ dependence on the oxidation time (oxide thickness) is nonmonotonous and depended on the cooling rate. In slowly cooled samples the increase of the EPR signal is accompanied by the decrease of Δv but, in fast cooled samples EPR signal and Δv increase simultaneously with increase oxidation time.

Absent of the cooling rate influence on the PD density and Δv dependence on the oxidation time at I(t) and $\Delta v(t)$ dependence intersection points show, that IMS by an appropriate choice of the SiO₂ film thickness disappear.

9:40am **EM+AN+MI+SS-WeM6 Unique Sensitivity to Deep Trap States Demonstrated by CREM of Broad Bandgap Dielectric Layers, Hagai Cohen, Weizmann Institute of Science, Israel; K.X. Steirer, Colorado School of Mines**

Chemically resolved electrical measurements (CREM) present an efficient and sensitive means for studies of structural-electrical inter-relationships in heterostructures. Operated in-situ to x-ray photoelectron spectroscopy (XPS), the technique is yet far from being fully exploited. Recent progress in our CREM instrumentation has, however, opened new opportunities to which this report is dedicated. Using broad-bandgap dielectric layers, such as SiO₂, SiON and ZnOS, we tested the CREM resolving power and sensitivity to charge trap states. These experiments yielded band diagrams with fine details on charge traps, which typically require the application of advanced optical techniques combined with the electrical characterization tools.

In addition, an intriguing process of doubly triggered conductance in ZnOS was observed. The ZnOS layers exhibited very poor conductance under either electrical or optical input signals, whereas simultaneous application of the two yielded extremely high sample currents. Based on the in-situ derived band diagram, a comprehensive explanation of the effect is provided. Moreover, we show how the CREM analytical tool can also provide a potential activator of future related devices.

11:00am **EM+AN+MI+SS-WeM10 Fabrication of Multilayered Optically Active Nanocrystal Solids by Surface Passivation using Metal Oxides: ALD vs CVD, Riya Bose, A.D. Dangerfield, University of Texas at Dallas; S.M. Rupich, University of Texas; Y.J. Chabal, A.V. Malko, University of Texas at Dallas**

Semiconductor nanocrystal quantum dots (NQDs) provide a powerful platform for optoelectronic applications with their size/shape/composition tunable properties and inexpensive solution based synthesis techniques. Integration into solid state devices requires deposition of NQD films, and often a controlled assembly of multilayered NQD structures to ensure maximum light absorption and optimum efficiency of the devices. However, thin film fabrication is found to degrade its properties compared to NQDs in solution, especially a decrease in the photoluminescence (PL) quantum yield (QY) is frequently observed. Also, the bottleneck for fabrication of multilayer NQD films remains the use of solution phase deposition methods, where the solvent in the subsequent step of deposition dissolves the initial layer until each NQD layer is rendered insoluble by means of any surface passivation technique. Surface passivation techniques also play a critical role to protect the deposited layers from oxidation and deterioration. An attractive method to passivate NQD films during the deposition as well as from environmental exposure is to overcoat them with various metal oxides grown using atomic layer deposition (ALD). Though there are few reports of ALD encapsulation of NQD films, they mostly attend to charge transfer-based devices and aim to improve carrier mobilities. Typically, such studies report a significant quenching of the PL intensity after encapsulation. In this study, we aim to investigate the exact growth mechanism of metal oxide layers by ALD on the surface of NQD films and how it, along with the ALD parameters,

affects their PL properties. With the aid of in-situ FTIR and ex-situ XPS measurements during Al₂O₃ deposition on oleic acid capped CdSe-ZnS core-shell nanocrystals, it is observed that the interaction of the metal precursor trimethyl aluminium (TMA) with the surface of the NQDs leads to the reorganization of the ligands as well as replaces Zn, leading to PL intensity quenching. In order to prevent this, we opted for a pulsed chemical vapour deposition (CVD) like approach for metal oxide deposition where simultaneous purging of both the metal and oxygen precursors leads to formation of metal oxide in a gas phase in the immediate vicinity of the NQD surface. We found that minimization of TMA interaction with the NQDs' surface indeed leads to enhancement of the PL intensity and elongation of carrier PL lifetime. These measurements provide clear indication of defect-free surface passivation proving that CVD-like Al₂O₃ encapsulation is a suitable technique for controlled deposition of multilayered NQD structures that preserves its optoelectronic properties.

11:20am **EM+AN+MI+SS-WeM11 The Role of Surface Oxides for the Optoelectronic Performance of III-V Semiconductor Nanowires, J. Colvin, A. Troian, O. Persson, A. Mikkelsen, Rainer Timm, Lund University, Sweden** III-V semiconductor nanowires (NWs) have a large technological potential within electronics, optoelectronics, and energy harvesting [1,2], mainly due to their flexibility in creating heterostructures by axial stacking during epitaxial growth. Because of their small diameter and their very large surface-to-volume-ratio, the performance of NW devices is strongly determined by surface properties. We have previously studied surfaces and surface oxides of semiconductor NWs by scanning tunneling microscopy and spectroscopy (STM/S) [3] as well as X-ray photoemission spectroscopy [4]. Here, we will correlate the surface properties of InAs and InP NW heterostructures with their electrical and photovoltaic behavior, which has been measured for individual upright-standing NWs using the STM tip as local nanoprobe [5].

InP and GaInP pin-junction NWs have been cleaned from their native oxide by annealing under atomic hydrogen background and re-oxidized by exposure to ambient conditions. By illuminating the InP NWs that were contacted by the STM nanoprobe, we observed a decrease of the open-circuit voltage from 0.75 V to 0.70 V upon native oxide removal and an increase back to 0.76 V upon re-oxidation, confirming the need of surface passivation for improving InP solar cells. However, the ideality factor of the NW pin-diodes remained constant at $n = 1.82$ upon oxide removal, but improved to $n = 1.67$ upon re-oxidation. Furthermore, our XPS results indicate the outdiffusion of Zn dopants from the p-doped NW segments, forming a Zn-rich shell around the NW.

A more significant effect of the presence of native surface oxide was found for InAs NWs which consist of one segment of wurtzite and one segment of zincblende crystal structure. Upon removal of the native surface oxide, we obtained an increase in conductivity of these NWs by two orders of magnitude, while reference NWs with pure wurtzite structure showed a slight decrease in conductivity with the same surface treatment. This effect can be explained by a staggered type-II surface band alignment at the wurtzite/zincblende interface of oxidized NWs, which turned into flat-band conditions upon oxide removal, as confirmed by nano-focus XPS measurements.

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11:40am **EM+AN+MI+SS-WeM12 Photonic Annealing of 2D Transition Metal Dichalcogenides for Tailored Optical Properties, Rachel Rai, K. Gliebe, University of Dayton; Air Force Research Laboratory; N.R. Glavin, R. Kim, A. Jawaid, R. Wheeler, L. Bissell, Air Force Research Laboratory; C. Muratore, University of Dayton**

Thin layers of transition metal dichalcogenides (TMD) have attracted significant interest in the field of optoelectronics due to their unique light absorption and emission properties in the visible frequency range. Development of bright, flexible, large area emission sources based on 2D materials using photonic annealing represents an exciting opportunity for future quantum systems. Here we introduce new correlations relating the optical properties of WSe₂, a well-known single photon emitter, to post-processing annealing techniques to include lasers, broadband radiation, and nanoscale electron beams. Modulation of the total energy flux during growth of amorphous TMD material to develop purely amorphous

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materials or materials with nanoscale nuclei was employed by the authors to examine effects of pre-existing nuclei on crystallization kinetics (i.e., activation energy) and the resulting optical properties. We correlate the wavelength and intensity of photoluminescence from WSe₂ deposited on plasma treated and as-received flexible substrates and present techniques to control film continuity and the areal density of free edges from islands on discontinuous films for tuning the intensity of optical emission. A significant increase in photoluminescence intensity is accompanied by a change in domain boundary density, correlating well to theory. Furthermore, examination of quantum confinement effects by producing nanoscale crystalline areas (between 5-50 nm) with precisely controlled volumes via electron beam radiation provides insight on light emission mechanisms.

12:00pm **EM+AN+MI+SS-WeM13 Polarity Control of GaN Nanowires on Diamond: Experiment and Theory**, *Karin Larsson*, Uppsala University, Sweden; *M. Hetzl*, *M. Kraut*, *T. Hoffmann*, *M. Stutzmann*, Technical University Munich, Germany

III-nitride nanowires on diamond substrates are of current interest for two different potential applications: (i) selectively grown n-type AlGaIn nanowires on p/i – diamond are promising for the electrical control and the efficient optical and electrical readout of individual NV-centers in diamond as qubits and (ii) AlGaIn/diamond n/p-heterodiodes are an interesting option for future ultraviolet LEDs and laser diodes. For both applications, the polarity of AlGaIn nanowires grown on diamond has a strong influence on the optoelectronic properties of the heterojunctions, because the polarization-induced interface charge strongly influences the details of the diamond/III-nitride band alignment. Thus, the growth of nanowire arrays with randomly fluctuating polarity will have a negative influence on the electronic properties of the heterojunctions.

In this presentation, we will discuss recent experimental results concerning the control of GaN nanowire polarity on diamond (111) substrates via different surface termination treatments (hydrogenation, oxygen termination, nitrogen radical exposure [1]). Systematic experimental investigations have shown that even very well ordered periodic nanowire arrays deposited by Selective Area Growth exhibit a high degree of polarity disorder. Diamond is a well-suited substrate for these investigations, since it supports several different types of stable surface structures which only differ by about one monolayer and have a strong influence on the preferred nanowire polarity. The effect of different surface terminations on nanowire polarity will be recapitulated. Furthermore, we complement these experimental investigations by theoretically studying the effect of diamond surface termination on the energetically preferred GaN polarity. First principle DFT-calculations are used to calculate the interface energies and the corresponding atomic configurations of the different diamond/GaN interfaces. Strong variations observed in the interface chemistry between diamond and GaN nanowires will be discussed based on the available experimental and simulation data.

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Nanometer-scale Science and Technology Division Room 203A - Session NS+2D+AN+MN+MP+SE-WeM

Micro, Nano and Opto Mechanics

Moderators: Robert Ilic, National Institute of Standards and Technology, Alokik Kanwal, NIST Center for Nanoscale Science and Technology

8:20am **NS+2D+AN+MN+MP+SE-WeM2 The Collective Behavior of Large Ensembles of Coupled MEMS Cantilevers with Varying Natural Frequencies**, *Christopher Wallin*, National Institute of Standards and Technology, Center for Nanoscale Science and Technology; *N. Dick*, Tel Aviv University, Israel; *R. De Alba*, *D.A. Westly*, National Institute of Standards and Technology, Center for Nanoscale Science and Technology; *S. Grutzik*, Sandia National Laboratories; *A.T. Zehnder*, *R.H. Rand*, Cornell University; *V.A. Aksyuk*, National Institute of Standards and Technology, Center for Nanoscale Science and Technology; *S. Krylov*, Tel Aviv University, Israel; *B.R. Ilic*, National Institute of Standards and Technology, Center for Nanoscale Science and Technology

The collective behavior of nonlinear, coupled micro- and nano-electromechanical (M/NEMS) resonators has been shown to exhibit a host of nontrivial dynamics including abrupt pattern switching, multistability, hysteresis, intrinsically localized modes, and synchronization. Additionally, M/NEMS resonator arrays are extremely responsive to environmental perturbations making them excellent candidates for sensing applications

when operated linearly. With our work, we investigate the collective dynamics of coplanar interdigitated arrays of prismatic microcantilevers operating in both the nonlinear and linear regimes.

Two opposing, partially interdigitated cantilever arrays with 100 cantilevers apiece were fabricated using a silicon-on-insulator wafer. The device consists of a unique geometry in which each array has cantilever lengths expanding linearly across the device in opposite directions giving a distribution of natural frequencies. The arrays were engineered to allow for large scale, nonlinear out-of-plane beam deflections through the removal of the entire silicon handle layer beneath the active array area.

For sufficiently large drive amplitudes, the resonators begin oscillating via combination parametric resonance (CPR) across the entire array. The CPR driven oscillations occur across a broad frequency band. The tunable coupling between nearest-neighbor cantilevers through fringing electrostatic fields provides a mechanism to vary the CPR response. Due to the sizable deflections, the device's nonlinearities are apparent including hysteresis effects. Our experimental results are supported and expanded by the development of a reduced order model based on the Galerkin decomposition which generates the leading features of our data including the CPR band.

When operating in the linear regime, the natural modes of the array have localized characteristics whereby a limited number of beams oscillate at each of the natural mode frequencies. Operating the device at higher harmonics increases mode separation as the propagation bands stretch. The distinct resonant peak separation coupled with the spatially confined modal response make higher harmonic operation of tailored, variable length cantilever arrays well suited for a variety of resonant based sensing applications.

8:40am **NS+2D+AN+MN+MP+SE-WeM3 Piezoelectric Optomechanical Systems**, *Krishna Coimbatore Balram*, University of Bristol, UK **INVITED**

Nanoscale optomechanical systems, which rely on the strong interactions between co-localised optical and mechanical modes in nanoscale cavities, have been explored for a wide variety of applications ranging from sensing to signal transduction [Aspelmeyer et al., Rev. Mod. Phys. (2014)]. In this talk, I will discuss piezoelectric optomechanical platforms for efficient signal transduction between the radio frequency (RF) and optical domain. We use GaAs as our model platform (Balram et al., Optica (2014), Nature Photonics (2016), Phys. Rev. Applied (2017)) and discuss some of the research opportunities and challenges in this field, especially as we move towards higher mechanical frequencies (> 10 GHz).

9:20am **NS+2D+AN+MN+MP+SE-WeM5 Absolute Deflection Measurements in a MEMS/NEMS Fabry-Perot Interferometry System**, *Roberto De Alba*, *C.B. Wallin*, *G. Holland*, National Institute of Standards and Technology; *S. Krylov*, Tel Aviv University, Israel; *B.R. Ilic*, National Institute of Standards and Technology

Micro- and nano-electromechanical systems (MEMS/NEMS) are among the most sensitive devices for detection of ultra-weak forces, masses, and displacements. The small scale of these structures affords them very high frequencies (MHz to GHz), high quality factors, rich nonlinear phenomena, and many other beneficial traits that make them ideal as sensors and testbeds of fundamental physics. Fabry-Perot laser interferometry is a widespread and robust technique for probing MEMS/NEMS devices because it is non-invasive and provides exceptional motion sensitivity (≈ 1 pm/Hz^{1/2}) from DC to roughly 100 MHz. This technique utilizes the silicon substrate beneath the MEMS/NEMS device as a static reference mirror; doing so provides common-mode noise rejection in contrast to interferometers that use an external reference mirror. Furthermore, this technique is compatible with a wide range of MEMS/NEMS materials, from common insulators and conductors to graphene and other atomically-thin membranes.

Despite the many strengths of this experimental technique, it suffers from two main drawbacks. Firstly, the measured signal becomes highly nonlinear for device displacements larger than $\lambda/4$, where λ is the laser wavelength. Secondly, because the silicon backplane is immovable, there is no simple or established technique for calibrating device motion. As such, published results utilizing this setup typically report deflection in "arbitrary units." In this work, we focus on fully characterizing the nonlinear aspects of a MEMS/NEMS Fabry-Perot interferometer and developing a generalized approach to calibrate device motion based the wavelength of light. We will demonstrate how to quickly and accurately determine both static and dynamic MEMS/NEMS deflection by measuring reflected laser power in the time domain. We will further show how a single calibration (made in the large-amplitude regime) can be applied to subsequent measurements

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taken at lower amplitudes as well as to measurements taken in the frequency domain (e.g. by a lock-in amplifier). Lastly, we will demonstrate the capability of imaging the first three vibrational modes of a MEMS cantilever by using a scanning laser.

9:40am **NS+2D+AN+MN+MP+SE-WeM6 Silicon on Insulator Electrostatically Actuated Bistable Cantilevers for Resonant Displacement/Acceleration Sensing**, O. HaLevy, E. Benjamin, N. Krakover, Y. Kessler, *Slava Krylov*, Tel Aviv University, Israel

Resonant accelerometers incorporating vibrating beams demonstrate higher sensitivity and better robustness when compared to their statically operated counterparts. Electrostatic softening of the beams electrostatically coupled to the proof mass allows to enhance sensitivity of the resonant accelerometers. The displacement of the proof mass affects the gap between the mass and the beam and results in the beam's frequency change, which is maximal in the vicinity of the critical limit points of the voltage-deflection curve. The use of the snap-through buckling for this purpose is attractive since it is fully reversible and does not involve contact. While double-clamped curved bistable beams designed to demonstrate snap-through behavior can serve as resonant acceleration sensors [1], they suffer from high sensitivity to temperature and residual stress.

In this work we report on a design and fabrication of an electrostatically actuated bistable resonant cantilever [2], which demonstrates low sensitivity to the temperature and to the residual stress. The concept is based on the tailoring of the actuating force in such a way that the beam in its initial "as fabricated" configuration is positioned in the vicinity of the critical point. This is achieved by designing the actuating electrodes to be significantly thicker than the beam. Our reduced order (RO) Galerkin and coupled finite elements (FE) models results show that the frequency to deflection sensitivity of the $L = 150 \mu\text{m}$ long, $h = 16 \mu\text{m}$ wide and $d = 1 \mu\text{m}$ thick cantilever can reach 20 Hz/nm. This is equivalent to the frequency to acceleration sensitivity of 388 Hz/g, obtained for the case of a $4 \text{ mm} \times 20 \mu\text{m}$ proof mass.

While the model results are promising, fabrication of the device incorporating the beams and the electrodes of the different thicknesses is challenging. We demonstrate fabrication of the $50 \mu\text{m}$ thick electrodes and $\approx 6 \mu\text{m}$ thick cantilevers from the same device layer of a Silicon on Insulator (SOI) wafer. Two-stage deep reactive ion etching (DRIE) process was used for an initial patterning of the electrodes and of the cantilever and for the thinning of the beams. We discuss the details of the fabrication process and preliminary experimental results.

[1] N. Krakover, B. R. Ilic and S. Krylov, "Displacement Sensing Based on Resonant Frequency Monitoring of Electrostatically Actuated Curved Micro Beams," *J. Micromech. Microeng.*, **26**, pap. 115006, 2016.

[2] N. Krakover, S. Krylov, "Bistable Cantilevers Actuated by Fringing Electrostatic Fields," *ASME Journal of Vibration and Acoustics*, **139**(4), 040908-040908-10, 2017.

11:00am **NS+2D+AN+MN+MP+SE-WeM10 Electron-Photon-Phonon Hybrid Systems Based on Compound Semiconductor Mechanical Resonators**, *Hiroshi Yamaguchi*, NTT Basic Research Laboratories, Nippon Telegraph and Telephone Corporation, Japan **INVITED**

The use of compound semiconductor heterostructures as the elastic materials in the fabrication of micro/nanomechanical resonators has advantages, such like the improvement of mechanical properties through strain engineering, optomechanical transduction through carrier-mediated coupling, and piezoelectrically controllable nonlinearity [1]. The hybrid properties play the essential role in the operation where the different excitations of phonons, photons, and electrons are mutually interacted. In this invited talk, I will review our recent activities studying the electronic [2], photonic [3], and phononic [4] functions in GaAs-based mechanical resonators.

[1] H. Yamaguchi, *Semicond. Sci. Technol.* **32**, 103003 (2017).

[2] Y. Okazaki, I. Mahboob, K. Onomitsu, S. Sasaki, and H. Yamaguchi, *Nature Commun.* **7**, 11132 (2016).

[3] H. Okamoto, T. Watanabe, R. Ohta, K. Onomitsu, H. Gotoh, T. Sogawa, and H. Yamaguchi, *Nature Commun.* **6**, 8478 (2015).

[4] M. Kurosu, D. Hatanaka, K. Onomitsu, and H. Yamaguchi, *Nature Commun.* **9**, 1331 (2018).

11:40am **NS+2D+AN+MN+MP+SE-WeM12 Size Dependent Mechanics of Elastomers**, *Le Li, N. Alsharif, K.A. Brown*, Boston University

Elastomers are fascinating materials owing to the fact that their mechanical properties are dictated by entropy. Due to their low modulus, chemical compatibility, and ease of processing, they are widely applied in fields from soft lithography to medical devices. While it is well accepted that they exhibit fascinating size-dependent mechanical properties when confined to thin films, the structure-property relationships that govern confined elastomers are difficult to unambiguously determine due to the mechanical influence of rigid support structures and unavoidable contributions from adhesion. As a result, a consensus regarding the moduli of elastomeric thin films has not emerged. Here, we present a combined computational and experimental approach to measure the true mechanical properties of thin elastomer films. First, we utilize extensive finite element simulations to determine a correction to the Hertzian contact model that depends upon a dimensionless film thickness and the polymer Poisson's ratio. In order to verify this correction, films composed of three different thermoplastics were studied using an atomic force microscopy (AFM) nanoindenting. Interestingly, all three were observed to soften when confined to films thinner than 100 nm, in agreement with literature reports of buckling experiments. To explore softer elastomeric materials that exhibit categorically different behavior, we extended this correction to the Johnson-Kendall-Roberts (JKR) model that considers adhesion in contact mechanics. Elastomer thin films with different crosslink densities were studied using AFM nanoindentation and finite element simulation to determine their moduli. We observed a drastic stiffening on all elastomeric films when they were confined to sub-micrometer thicknesses. More importantly, modulus of all sub-100 nm elastomer films converges to the same trend regardless of bulk crosslink density. We present a hypothesized molecular model explaining this behavior. These results shed new light on the nanomechanics of elastomers and provide a general process for exploring size-dependent mechanics in polymers.

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MEMS and NEMS Group

Room 202B - Session MN+2D+AN+NS-WeA

IoT Session: MEMS for IoT: Chemical and Biological Sensing

Moderators: Robert Davis, Brigham Young University, Sushma Kotru, The University of Alabama

2:20pm MN+2D+AN+NS-WeA1 BioMEMS for Eye Applications, Yu-Chong Tai, California Institute of Technology

INVITED

The field of Micro-Electro-Mechanical Systems (MEMS) has advanced tremendously for the last 20 years. Most noticeably, however, the field has mostly advanced in microsensors such as pressure sensors, accelerometers, gyros, microphones for cell phone and smart instrumentation applications. Looking forward though, in my opinion, one future direction of MEMS/NEMS is for micro biomedical devices. Among many possible biomedical applications, one challenging but promising branch is micro implants. Why micro implants? Body tissues (especially neurons), once severely damaged, do not repair or regenerate easily and often leave behind permanent debilitating deficits. Engineering implant technologies to interface intact tissues and/or to replace defective functions have continued to be the main solutions for many diseases. As our world is facing more severe aging population problems, significant growth in implant applications is foreseeable. As a matter of fact, there are already many existing commercially available implants such, as pacemakers and cochlear implants, but they all have a lot to improve. For examples, cardiovascular implants like defibrillator and pacemakers are still bulky, mechanically rigid, power hungry, and functionally limited. The future implants should be even smaller, flexible, power efficient and more versatile so that they can be used at places not possible before. This talk will review the research of implants done at the Caltech MEMS lab. More specifically, this talk will focus on bioMEMS implant devices to treat eye diseases. Examples of devices will cover the four major ophthalmic diseases, i.e., cataract, glaucoma, age-related macular disease and diabetic retinopathy that make of close to 80% of world blindness. It is believed that BioMEMS can also have many other opportunities for other organs in our body too.

3:00pm MN+2D+AN+NS-WeA3 Real-Time, Single Cell, Size Measurements using a Facile, Multimode Microwave Resonator, Selim Hanay, H. Aydogmus, A. Secme, H.S. Pisheh, M. Kelleci, U. Hatipođlu, Bilkent University, Turkey

In this study, a facile microwave sensor is designed and fabricated to detect transient cells one by one and extract their morphological and electrical properties in real time, without labeling. Multiple modes can be measured by multiplexing the electronic frequencies to obtain multiple analytic parameters at the same time. Our simple fabrication technique obviates the need to complex fabrication process.

A microwave sensor, in the form of a microstrip line resonator, is constructed by fixing copper tape at the back and the front side of a 1-mm thick glass slide. The backside is covered entirely with the tape to form a ground plane; on the front side, a copper tape was thinned within a few mm, extended across the slide and terminated with SMA feed through. On the front side, just below the copper tape, five capillary tubes are placed to transport the cells into the active sensing region. Microwave signals are transmitted through the two SMA ports at the end of the glass slide, perpendicular to the flow. The resonator is formed by electrically shorting the input/output ports. An initial characterization of the device is done by using spectrum analyzer so that its first and second order mode frequencies are obtained.

A digital phase-locked loops (PLL) measurement system with PI controller was constructed to track the resonance frequencies of the first two modes simultaneously in real-time. The PLL system tracks the two modes of the microstrip line resonator to sense the frequency shifts originating from the passage of the cells in the capillary.

As a proof of concept, initial PLL measurements were done with DI water. As water flows through the tube, frequency shifts around 100 kHz were observed in both modes. Later on, wildtype *Skbr3* breast cancer cells were flown through the same capillary. Frequency shifts in both modes were the responses of the resonator to the passage of the *Skbr3* cells beneath microstrip-line. The ratio between the first and second mode frequency shifts can be used determine the location of each cell by two-mode theory. The analyzed data indicates almost a constant slope, verifying the

positional response of the sensors. Moreover, the size distribution of the cells is cumulated around a contour line for constant size as expected.

Earlier, we had detected single cells and distinguished different oncogenic cell lines using a PDMS based device. With this work, single-cell detection and sizing are accomplished with a device paradigm that does not require any lithography, metal deposition under vacuum or precise alignment of electrodes.

We acknowledge funding from European Research Council (ERC) Starting Grant (REM, 758769).

4:20pm MN+2D+AN+NS-WeA7 Magnetic Microsystems for Communications, Rob Candler, University of California at Los Angeles

INVITED

We are witnessing a rapid expansion of embedded devices (IoT) that have a variety of functions but a common requirement, to communicate with one another. These devices will be connected on a scale previously unseen, and they will therefore require an approach to efficiently generate and receive electromagnetic waves in a small form factor. One such approach is to rethink the way electrically small antennas operate, shifting from a current-based antenna to a voltage-controlled multiferroic antenna. Multiferroics are material systems with coupled magnetic and electrical properties, and they offer a new route for the miniaturization of magnetic field-coupled devices. Multiferroic systems allow for the conversion of magnetic flux to a voltage (and vice versa) without the need of a wire loop, avoiding inefficiencies due to Ohmic loss. *In particular, strain-coupled*

heterostructures of magnetostrictive and piezoelectric materials have received much attention, as they can offer magneto-electric coupling many orders of magnitudes higher than found in single-phase materials. A rapidly emerging research space in multiferroics is the development of miniature wireless devices, such as antennas and energy harvesters, taking advantage of the efficient flux-to-voltage conversion of multiferroics. In this talk, I will present work showing the impact of multiferroic coupling on the ferromagnetic resonance in GHz Bulk Acoustic Wave resonators, as well as investigations in frequency mixing from non-linear multiferroic affects.

These results are all in support of our goal create a microscale multiferroic antenna that is orders of magnitude more efficient than its classical antenna counterpart.

Furthermore, continued miniaturization of existing and emerging components that use magnets (atomic clocks, quantum computing, magnetic memory) will increase their sensitivity to external magnetic fields as well as the crosstalk between components. To address this need, we are developing techniques for on-chip magnetic shielding using multiple layers of permalloy. We will present recent results showing microscale magnetic shields fabricated by electroplating multiple permalloy layers into molds, as well as milliscale shields that were conformally electroplated on 3D printed sheaths.

5:00pm MN+2D+AN+NS-WeA9 MEMS-Based Resonant Sensors for IoT Applications, Oliver Brand, M. Kim, P. Getz, Georgia Institute of Technology

INVITED

The presentation discusses resonant microsensors, in which the measurand affects a characteristic of the resonance behavior of a resonant microstructure or a resonant circuit, such as its resonance frequency or quality factor. Resonant sensing is a very versatile sensing approach and can be adapted to a large variety of physical, chemical and biological measurands. Especially when using the resonance frequency as the sensing signal, high resolution is achievable since frequencies can be measured accurately. The presentation will highlight two possible implementations of resonant chemical sensors for Internet of Things (IoT) applications, a cantilever-based electromechanical resonator and a purely electrical L-C resonance circuit.

The first example is an electro-mechanical resonant chemical sensor based on a silicon hammerhead structure coated with a polymeric sensing film for the detection of volatile organic compounds. The presentation will highlight how proper selection of the resonance mode, in this case an in-plane vibration mode, and device geometry can improve device performance and how fast temperature modulations of the resonant sensors enable the observation of signal transients that contain additional analyte information. The sensors are fabricated using a CMOS-compatible bulk-micromachining process, have resonance frequencies between 400-800kHz and achieve sub-ppm limits of detection for select analytes.

The second example is a purely electrical resonant chemical sensor in form of a flexible and stretchable L-C (inductor-capacitor) sensor, which is battery free and can be wirelessly interrogated. To achieve stretchable

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sensor characteristics, the spiral inductor and interdigitated capacitor structures are formed by a liquid metal, eutectic gallium-indium (EGaIn). A subtractive reverse stamping technique is used to form the conducting liquid metal lines with dimensions as small as $2\mu\text{m}$ inside PDMS microchannels and a 3D heterogeneous integration technique is applied to vertically stack and electrically interconnect the capacitor and inductor structure. Liquid and gaseous analytes change the capacitance and are detected by wirelessly measuring the resonance frequency of the L-C circuit around 143MHz.

5:40pm **MN+2D+AN+NS-WeA11 Etched Silicon Microcolumn For Tunable Thermal Gradient Gas Chromatography**, *Aaron Davis, P. Schnepf, P.S. Ng, R.R. Vanfleet, R.C. Davis, B.D. Jensen*, Brigham Young University

The connection of the digital and physical world will be strengthened by chemical sensors that can measure complex mixtures of molecules. Gas chromatography is the gold standard for identification of volatiles and gases. Conventional gas chromatography systems have unparalleled resolution, but are large and power intensive. Microcolumn gas chromatographs are more portable but have dramatically reduced resolution. Combining the resolution of conventional systems with the size factor of micro systems is important for improving the affordability and portability of high performance gas analysis. Recent work has demonstrated feasibility of high resolution separation of gases in a benchtop-scale short-column system by controlling thermal gradients through the column. In order to further decrease the size of a gas chromatography system, microfabrication techniques were used to demonstrate the fabrication of a thermally controllable micro-scale gas chromatographic column with a small footprint (3 cm square). To fabricate microcolumns we are using deep-reactive-ion-etching, nickel evaporation, and wafer bonding. The design of the 20 cm column utilizes 21 individually controllable thin film heaters and solid conduction cooling to produce the desired thermal profile.

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Room 202B - Session MN+2D+AN+MP+NS-ThM

Optomechanics and 2D NEMS

Moderator: Max Zenghui Wang, University of Electronic Science and Technology of China

8:00am **MN+2D+AN+MP+NS-ThM1 Towards Microwave to Telecom Wavelength Quantum Information Transfer using Cavity Optomechanics, John Davis**, University of Alberta, Canada **INVITED**

The past few years have seen the rapid maturation of quantum information processors, particularly in the category of superconducting microwave circuits. With claims from leading companies that they will commercialize quantum processors in the next five years, we must wonder what quantum technologies should be developed in tandem to fully utilize these processors. For example, we are all acutely aware that while our personal computers are powerful, they are considerably more useful and interesting when networked together. So how can we likewise network quantum processors? Especially since the microwave signals of superconducting processors cannot be transmitted at room temperature without thermal decoherence. What if instead, one could link superconducting processors together through existing fiber-optic networks, which are already capable of long distance quantum information transfer? Hence the development of a transducer of quantum information from the microwave to telecom domain has become highly desirable. I will describe the current state of microwave to optical transducers, and how our lab is working towards this goal. Specifically, I will discuss the progress and challenges associated with the development of fiber-coupled telecom-wavelength cavity optomechanical resonators, and 3D superconducting microwave cavities, operating at millikelvin temperatures. I will also discuss ongoing collaborations that could enable implementation of quantum information transducers in a large-scale fiber network in Alberta.

11:20am **MN+2D+AN+MP+NS-ThM11 Reconfigurable Resonant Responses in Atomic Layer 2D Nanoelectromechanical Systems (NEMS), Zenghui Wang**, University of Electronic Science and Technology of China; R. Yang, P.X.-L. Feng, Case Western Reserve University

Atomic layer semiconducting crystals have emerged as a new class of two-dimensional (2D) materials, exhibiting great promises for both fundamental research and technological applications. Their outstanding electromechanical properties make these materials ideal for constructing novel 2D NEMS, providing opportunities for leveraging their unique device properties across multiple information-transduction domains, at scales down to individual atomic layers. One particularly interesting category of 2D NEMS is 2D nanoelectromechanical resonators, which hold potentials for making the next generation RF signal transduction and processing components, with miniaturized size, ultra-low power consumption, and compatibility with transparent and flexible circuits.

Towards future applications in the 5G era, multi-band RF signal handling capability is desired, as the number of bands each mobile device need to have access to significantly increases, and it would be impractical to simply increase the number of RF components that can only function under one RF frequency, as the space required for mounting such components scales with the number of bands. Therefore, ultralow-power tunable and reconfigurable RF devices that can adapt to different frequencies would be one solution to this challenge.

Here we present experimental demonstration of nanomechanical resonators based on layered MoS₂ atomic crystals that have reconfigurable resonant responses. By carefully studying the temperature-dependent frequency response in such MoS₂ resonators[1], we discover clear, repeatable hysteretic behavior as the device temperature is changed[2]. Leveraging this phenomenon, we achieve switchable resonance frequency f_{res} in such devices by using heating and cooling pulses. Specifically, for an example MoS₂ resonator, during heating pulses, the f_{res} decreases to ~20MHz. Once the device recovers to room temperature, f_{res} stabilizes at ~26MHz. During cooling pulses, f_{res} increases to ~29MHz, and upon reverting to room temperature f_{res} stays at ~24.5MHz, which is clearly different than the other room temperature state. Our findings suggest that such atomic-layer MoS₂ NEMS resonators could be used towards developing reconfigurable RF components whose frequency response can be switched between different states.

[1] R. Yang, et al., *IEEE UFFC*, pp 198-201, 2015. [2] Z. Wang, et al., *IEEE UFFC*, pp 783-786, 2015.

11:40am **MN+2D+AN+MP+NS-ThM12 Cavity Optomechanics: Dynamics and Applications, Eyal Buks**, Israel Institute of Technology, Israel **INVITED**

The field of cavity optomechanics deals with a family of systems, each composed of two coupled elements. The first one is a mechanical resonator, commonly having a low damping rate, and the second one is an electromagnetic cavity, which typically is externally driven. Both radiation pressure and bolometric force can give rise to the coupling between the mechanical resonator and the cavity. In recent years a variety of cavity optomechanical systems have been constructed and studied, and phenomena such as mode cooling, self-excited oscillation, and optically induced transparency have been investigated. The first part of the talk will be devoted to some dynamical effects including synchronization and intermittency. In the second part some applications of optomechanical cavities for sensitive sensing will be discussed.

Nanometer-scale Science and Technology Division

Room 102B - Session NS+AN+EM+MI+MN+MP+PS+RM-ThM

Nanopatterning and Nanofabrication

Moderators: Brian Hoskins, National Institute of Standards and Technology (NIST); Meredith Metzler, University of Pennsylvania; Leonidas Ocola, IBM Research Division, T.J. Watson Research Center

8:00am **NS+AN+EM+MI+MN+MP+PS+RM-ThM1 Femtosecond Laser Processing of Ceria-Based Micro Actuators, J. Shklovsky**, Tel Aviv University, Israel; E. Mishuk, Weizmann Institute of Science, Israel; Y. Berg, Orbotech Ltd, Israel; N. Vengerovsky, Y. Sverdlov, Tel Aviv University, Israel; I. Lubomirsky, Weizmann Institute of Science, Israel; Z. Kotler, Orbotech Ltd; S. Krylov, Y. Shacham-Diamand, Erez Benjamin, Tel Aviv University, Israel

The integration of piezoelectric and electrostrictive materials into micromachined Si devices is viewed as an important technological milestone for further development of Microelectromechanical Systems (MEMS). Recently, it was demonstrated that gadolinium-doped ceria (CGO) exhibits very large electrostriction effect, which results in large electrostrictive strains and high energy densities under very low frequencies (0.01 – 1 Hz). Lead-free CGO is chemically inert with respect to Si, making it an attractive candidate for implementation in MEMS actuators. However, the integration of CGO into MEMS devices is challenging due problems associated with using conventional patterning techniques involving lithography and etching.

In this work, we have successfully created functional double-clamped beam micro-actuators made of CGO films confined between the top and bottom Al/Ti electrodes. The stack containing the electrodes and the $\approx 2 \mu\text{m}$ -thick CGO film was first blanket-deposited on top of the Si wafer. Cavities were then deep reactive ion etched (DRIE) in the wafer leading to forming of the free-standing rectangular membranes, $1.5 \text{ mm} \times 0.5 \text{ mm}$ in size. Finally, $\approx 1.2 \text{ mm}$ long and $\approx 100 \mu\text{m}$ wide the double-clamped beams were cut from the membranes using a femtosecond (fs) laser, demonstrating an unharmed technique for CGO patterning. Laser pulse energies, overlaps and number of line passes were varied during the experiments, to achieve successful cuts through the suspended layer by a clean ablation process. The optimized process conditions were found at a fluence of $\sim 0.3 \text{ J/cm}^2$ for a pulse width of 270 fs, where minimal damage and accurate processing was achieved with minimized heat-affected zones.

Resistivity measurements between the top and the bottom electrodes before and after fs laser cutting revealed that the cutting has no influence on the electric parameters of the device and no electrical shorts are introduced by the laser processing. Vertical displacement measurements under bipolar AC voltage (up to 10 V), at the frequency range of 0.03 – 2 Hz, demonstrated the functionality of the micro-actuator. A displacement of $\approx 45 \text{ nm}$ at the voltage of 10 V at 50 mHz was achieved. The actuator didn't show any mechanical or electrical degradation after continuous operation. Our data confirm that fs laser cutting is a useful technique for processing CGO films. The developed techniques may be expanded to other materials used for fabrication of MEMS devices, enabling fast, high yield and high-quality patterning of materials that are challenging to pattern using conventional etching-based methods.

*Three first authors contributed equally to this abstract.

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8:20am **NS+AN+EM+MI+MN+MP+PS+RM-ThM2 Synthesis of Functional Particles by Condensation and Polymerization of Monomer Droplets in Silicone Oils**, *Prathamesh Karandikar, M. Gupta*, University of Southern California

The initiated chemical vapor deposition (iCVD) process is an all-dry, vacuum process used to deposit a wide variety of functional polymers. Typically, the monomer and initiator radicals are introduced simultaneously at process conditions leading to undersaturation of monomer vapors. In this work we report a sequential vapor phase polymerization method in which monomer droplets were first condensed onto a layer of silicone oil and subsequently polymerized via a free radical mechanism to fabricate polymer particles.

The viscosity of the silicone oil was systematically varied from 100 cSt through 100,000 cSt. A heterogeneous particle size distribution was produced at low viscosities of silicone oil where the smaller particles were formed by the cloaking and engulfment of monomer droplets nucleated at the vapor-liquid interface and the larger particles were formed by coalescence inside the liquid. Coalescence could be inhibited by increasing the viscosity of the silicone oil leading to a decreased average radius and a narrower size distribution of the polymer particles. A transition to polymer film formation was observed for the 100,000 cSt silicone oil substrates. We studied the polymerization of two different monomers, 4-vinyl pyridine and 2-hydroxyethyl methacrylate, since these polymers have a variety of useful properties such as pH-responsiveness and biocompatibility. Our process enables fabrication of functional particles with average diameters ranging from 100 nm – 500 nm with fast reaction times (≈ 15 min). The advantages of our method for the fabrication of polymer particles are that it does not require surfactants or organic solvents and features short reaction times compared to conventional polymer particle synthesis methods such as emulsion polymerization.

8:40am **NS+AN+EM+MI+MN+MP+PS+RM-ThM3 Competition Between Scale and Perfection in Self-assembling Structures**, *James Liddle*, NIST Center for Nanoscale Science and Technology **INVITED**

Biology relies on self-assembly to form complex, highly-functional structures, inspiring the search for synthetic systems capable of forming similarly complex structures. Such systems typically operate under diffusion-limited, near-equilibrium conditions, making the problem even more challenging. Multi-functional, molecularly-addressable nanostructures of arbitrary shape can be built using DNA-mediated self-assembly. While this is a powerful method, and recent developments in DNA nanostructure fabrication have expanded the available design space, fabrication based on DNA alone can suffer from low yields and is hampered by the need to trade off size and mechanical rigidity.[1,2]

We have been working to both understand the factors that limit the yield of self-assembled structures, and to devise approaches to overcome them. As the number of discrete components used to assemble a structure increases, yield decreases exponentially. We circumvent this limit, by using a two-stage, hierarchical self-assembly process, which allows us to create large structures with high yield.[3] Our process employs a small number of discrete, sequence-specific elements to shape the structure at the nanoscale and define the large-scale geometry. A generic building block – a DNA binding protein, *RecA* – rigidifies the structure without requiring any unnecessary information to be added to the system.

Blending sequence-specific and structure-specific elements enables us to expand the self-assembly toolbox and make micrometer-scale, rigid, molecularly-addressable structures. More generally, our results indicate that the scale of finite-size self-assembling systems can be increased by minimizing the number of unique components and instead relying on generic components to construct a framework that supports the functional units.

[1] Murugan, A., Zou, J. & Brenner, M. P. Undesired usage and the robust self-assembly of heterogeneous structures. *Nat. Commun.* **6**, 6203, doi:10.1038/ncomms7203 (2015).

[2] Schiffels, D., Liedl, T. & Fygenon, D. K. Nanoscale structure and microscale stiffness of DNA nanotubes. *ACS Nano* **7**, 6700-6710, doi:10.1021/nn401362p (2013).

[3] Schiffels, D., Szalai, V. A., Liddle, J. A., Molecular Precision at Micrometer Length Scales: Hierarchical Assembly of DNA-Protein Nanostructures, *ACS Nano*, **11**, 6623, (2017)

9:20am **NS+AN+EM+MI+MN+MP+PS+RM-ThM5 Polymer Templated Annealing of DNA Patterned Gold Nanowires**, *Tyler Westover, B. Aryal, R.C. Davis, A. Woolley, J. Harb*, Brigham Young University

Using DNA origami as a bottom up nanofabrication technique, gold nanowires are formed via directed assembly of gold nanorod seeds and connected by electroless plating. This metal deposition process results in wires with low conductivities compared to bulk gold. Junctions between plated seeds are likely the cause of this low conductivity. Annealing of the nanowires could potentially improve the conductance, however, nanowire annealing at low temperatures (200° C) results in wires coalescing into beads. A polymer encapsulation layer was deposited to maintain overall nanowire shape during annealing. The polymer templated anneal resulted in a resistance reduction, in some cases, to below 1000 ohms. Resistance measurements were performed using a four point resistance configuration. Electrical contacts to the randomly oriented 400 nm long wires were made by electron beam induced deposition. Nanowire morphology was measured before and after annealing by scanning electron and high resolution transmission electron microscopy.

11:00am **NS+AN+EM+MI+MN+MP+PS+RM-ThM10 Directed Self-assembly of Block Copolymers for Applications in Nanolithography**, *Paul Nealey*, University of Chicago **INVITED**

DSA of block copolymer films on chemically nanopatterned surfaces is an emerging technology that is well-positioned for commercialization in nanolithography and nanomanufacturing. DSA of (PS-*b*-PMMA) films on lithographically defined chemically nanopatterned surfaces is one focus of our activities in which the main research objectives revolve around understanding the fundamental thermodynamics and kinetics that governs assembly, and therefore patterning properties such as 3D structure, perfection, and processing latitude. A second focus is to use the physical and chemical principles that we have elucidated for DSA of PS-*b*-PMMA towards the development of block copolymer systems capable of self-assembling into the sub 10 nm regime and continuing to meet the stringent constraints of manufacturing. The research is enabled by the recent development of techniques to combine metrology tools (TEM tomography, GISAXS, RSoXS, high-speed APF), theoretically informed coarse grained models, and evolutionary algorithms to quantitatively determine and predict the independent process and material parameters that result in different 3D structures of assembled domains.

11:40am **NS+AN+EM+MI+MN+MP+PS+RM-ThM12 Three Dimensional Mesoporous Silica Nanowire Network Fabricated by Metal-Assisted Chemical Etching**, *Deepak Ganta, C. Guzman, R. Villanueva*, TAMIU

Mesoporous nanowires have gained huge attention due to their applications in energy and sensing. The high surface area along with the quantum confinement effect lead to improved performance of the electrochemical devices during energy conversion and storage. 3D structure or nanowire network improves the reaction site surface area even further along all the three dimensions, enhancing both light and heat absorption. There is also a huge demand for inexpensive, non-lithographic methods to fabricate 3D network of nanowires, which are also mesoporous, with better control of both dimensions and porosity, over a large surface area. They can be very useful in some broad range applications such as solar energy conversion, energy storage, water harvesting, environmental control, bio-sensing, and thermoelectrics.

To address the problem, we report a simple and inexpensive method of fabricating 3D mesoporous Si nanowire network by metal-assisted chemical etching (MacEtch). Degenerately doped p-type silicon or p+ silicon wafer (0.001 ~0.005 Ω -cm) was coated with about 22 nm silver film at 350 °C for 5~6 hours in a vacuum furnace (pressure < 3 \times 10⁻⁷ Torr). Scattered silver particles with different sizes were formed as a result of the dewetting process. Then we deposited 10~11 nm of noble metal (Au) at 0.5 Å/s rate, followed by silver lift-off to obtain an Au mesh as an etching mask. The mixture of a chemical solution of HF: H₂O₂: Ethanol = 30:1:1 is used as a chemical etchant under room temperature. The time of immersion of the silicon wafer in the etchant effects the aspect ratio of the silicon nanowire array. After MachEtch, the Au is removed by immersing the sample in the aqua regia solution. The ratio of the chemicals in the etchant will affect the

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pore size. The aspect ratio of the silicon nanowire network can be controlled by the etching rate. The etching rate was roughly one $\mu\text{m}/\text{min}$. The 3D network is formed as the length of the 1D silicon nanowires (50 nm -100 nm) was varied, followed by critical point drying to carefully control the uniformity of 3D silicon nanowire network on the entire surface area of the 6-inch silicon wafer.

Analysis of the 3D mesoporous silicon nanowire network was conducted using Scanning Electron microscopy (SEM), and the top view image confirmed the 3D network of silicon nanowires. The pore sizing (2-50 nm) along with the crystallinity confirmed from the high-resolution transmission electron microscopy (TEM) images with the diffraction patterns.

12:00pm **NS+AN+EM+MI+MN+MP+PS+RM-ThM13 Enhancing Light Extraction from Free-standing InGaN/GaN light Emitters Using Bio-inspired Backside Surface Structuring**, *L. Chan, C.D. Pynn, S.P. DenBaars, Michael Gordon*, University of California at Santa Barbara

A simple, scalable, and reproducible nanopatterning method to create close-packed (moth-eye like) patterns of conical nano- and microscale features on InGaN/GaN LED surfaces, and on the backside outcoupling surface of LED devices, is presented. Colloidal lithography via Langmuir-Blodgett dip-coating using silica masks ($d = 170\text{--}2530\text{ nm}$) and Cl_2/N_2 -based plasma etching produced features with aspect ratios of 3:1 on devices grown on semipolar (20-21) GaN substrates. The resulting InGaN/GaN multi-quantum well (MQW) structures were optically pumped at 266/405 nm, and light extraction enhancement was quantified using angle-resolved photoluminescence (PL). A 4.8-fold overall enhancement in light extraction (9-fold at normal incidence) relative to a flat outcoupling surface was achieved using a feature pitch of 2530 nm. Extraction enhancement occurs due to the graded-index (GRIN) effect and breaking of the TIR condition via increased diffuse scattering and diffractive effects, the importance of which evolves with moth-eye feature size. PL results also demonstrate that colloidal roughening, which has greater geometric tunability and works on any GaN orientation, is equivalent to current, c-plane only photoelectrochemical (PEC) roughening methods. Patterning the outcoupling backside of a semipolar device, rather than the topside, is also a technologically feasible approach to fabricate electrically pumped devices because it avoids issues associated with making large area (topside) p-contacts, etching close to or into the active emitter region (destroying the MQWs), or disrupting guided modes in thin-film LEDs layers on sapphire. Because of its simplicity, range of optical control, and wide substrate compatibility, the colloidal lithography technique is a promising alternative to existing commercial processes and a future pathway for enhanced extraction engineering in free-standing polar, nonpolar, and semipolar III-nitride LEDs.

MEMS and NEMS Group

Room 202B - Session MN+2D+AN+NS-ThA

Nonlinear and Thermal Resonators

Moderators: Meredith Metzler, University of Pennsylvania, Christian Zorman, Case Western Reserve University

2:20pm **MN+2D+AN+NS-ThA1 Embracing Nonlinearity and Thermal Fluctuations in Nanomechanics**, *D. Lopez, David Czaplewski, C. Chen*, Argonne National Laboratory; *D. Zanette*, Centro Atomico Bariloche, Argentina; *S. Shaw*, Michigan State University **INVITED**

The field of micro-mechanics is now a well-established engineering domain with demonstrated impact in fundamental science and product development. Unfortunately, as the dimensions of the devices are reduced from the micro- to the nano-scale, the direct scaling of the fundamentals principles and fabrication processes cease to work. When going from micro- to nano-mechanical systems, MEMS to NEMS, the devices linear dynamic range can be reduced to the point where the amplitudes needed for lineal response are below the noise level and, as a consequence, operation in the nonlinear regime is unavoidable. Furthermore, thermal fluctuations and fluctuation-induced forces become relatively stronger causing significant changes in their dynamic response and on the manner in which they interact with the surrounding environment. This combination of nonlinear dynamics and high sensitivity to fluctuations has been seen as a deleterious combination for the advance of nano mechanical devices.

Rather than continuing to struggle to avoid these phenomena, it is of interest to consider how micro/nanosystem might effectively capitalize on this nonlinear fluctuating response. In this talk, I will demonstrate that nonlinearity offers unique possibilities for the controlled response of micro and nano mechanical devices and, thereby, a host of novel application opportunities. Examples of these opportunities include the development of compact frequency sources with low phase noise, the engineering of dissipation reservoirs to manipulate energy decay processes, and the enhancement of synchronization range between microscopic and macroscopic oscillators.

3:00pm **MN+2D+AN+NS-ThA3 Probing Ion Radiation Effects in Silicon Crystals by 3D Integrated Resonating Thin Diaphragms**, *Hailong Chen, H. Jia, V. Pashaei*, Case Western Reserve University; *W. Liao, C.N. Arutt, M.L. McCurdy*, Vanderbilt University; *P. Hung*, The Aerospace Corporation; *R.A. Reed, R.D. Schrimpf, M.L. Alles*, Vanderbilt University; *P.X.-L. Feng*, Case Western Reserve University

Space radiation (*e.g.*, solar, galaxy) and man-made radiation environments (*e.g.*, nuclear plant) can expose devices to radiation at doses that may lead to severe damage [1]. In recent decades, a large body of work has been performed to understand radiation effects on mainstream solid state electronic devices [1-3], in particular on MOS devices [2] and integrated circuits [3]. Lately, microelectromechanical systems (MEMS) have seen widespread adoption in consumer, military and aerospace products due to their small size, low power consumption, and in some cases, monolithic integration with electronics [4]. As such, the reliability of MEMS devices for many applications in relatively benign environments has been well established [5]. However, the study of impact on mechanical properties due to radiation-induced damages is an area where limited research has been conducted.

In this work, we report on experimental investigation of heavy ion radiation effects on mechanical properties of Si crystals, by exploiting a novel 3D scheme of using 5 vertically stacked micromachined vibrating Si diaphragms (2 mm × 2 mm × 2 μm) exposed to oxygen ions. Simulations find the stop range of oxygen ions in Si is 7.3 μm. A Pelletron system is employed to irradiate oxygen ions into the Si diaphragms (10.3 MeV, with a dose of 5.6 × 10¹³/cm²). Before and after radiation, multimode resonances are characterized in vacuum by using an ultrasensitive optical interferometry system. We have observed that diaphragms D1 and D2, which oxygen ions are expected to pass completely through, present modest multimode redshifts ranging from 0.85 kHz to 1.67 kHz, and 0.85 kHz to 1.19 kHz, corresponding to an average fractional frequency shift of 10.5% and 7.0%, respectively. In contrast, for devices D3 and D4, in which most ions are expected to stop, each resonance peak shifts much more dramatically, with a frequency shift of 27.3% and 20.4%. We attribute these large shifts to the very large capture area of the diaphragms, the very heavy and energetic oxygen ions, and high ion dose. Device D5 shows minimal frequency shifts among the five diaphragms because few oxygen

ions reach and interact with this device layer. The diaphragm stack exhibits outstanding capability for probing radiation damages in MEMS, not only able to capture the radiation events obviously, but also help analyze different amount and types of damages induced in each stacking layer.

[1] L. Gregory, *et al.*, Proc. IEEE. **62**, 1974. [2] J. R. Srouf, *et al.*, Proc. IEEE. **76**, 1988. [3] H. L. Hughes, *et al.*, IEEE Trans. Nucl. Sci. **50**, 2003. [4] N. Arutt, *et al.*, Semicond. Sci. Technol. **32**, 2017. [5] H. R. Shea, Proc. SPIE. **7928**, 2011.

3:20pm **MN+2D+AN+NS-ThA4 An Array of Thermally-actuated Nanoresonators for Real-time Mass Spectrometry**, *Martial Defoort, M. Sansa, M. Gély, G. Jourdan, S. Hentz*, CEA/LETI-University Grenoble Alpes, France

Micro/Nano-ElectroMechanical Systems (M/NEMS) have attracted much attention in the last years in the mass spectrometry field. They feature high sensitivity, charge independent and single particle detection capabilities, in a mass range where conventional mass spectrometry struggles, hampering the analysis of large mass objects like protein complexes or viruses [1-4].

In general the size and mass of the device defines the size and mass ranges of the particles to measure for frequency tracking and point mass approximation purposes. However, as many silicon M/NEMS are electrostatically actuated, the gap between the driving electrode and the resonator becomes a critical parameter. While for many applications this gap should be as small as possible for high efficiency actuation and high signal-to-noise ratio, a particle landing within the gap results in a catastrophic failure of the device through electrical short-circuit or mechanical anchoring.

We present a new actuation scheme for doubly-clamped beams which relies on the thermal expansion of nano-actuators in silicon due to Joule heating, located close to the anchor of the resonator (Fig. 1), that we demonstrate to work in an array of 20 NEMS (Fig. 2). Unlike some thermoelastic actuation schemes [5], the technique we propose does not require an additional layer (of, for example, a metal) and is readily CMOS-compatible. Because of their small size and thermal capacity, the thermal time constant of the actuators is small enough to drive the resonator up to several 100's MHz with large efficiency and to actuate the two first flexural modes of the same device simultaneously, which is required for single particle mass sensing. The detection scheme uses the piezoresistive gauges located on the other end of the beam, as previously presented [6]. We compare the performance of this actuation technique with a standard electrostatic scheme both on the same array and demonstrate the thermal actuation does not affect the level of frequency fluctuations limiting the device mass resolution (Fig. 3).

1. Hanay *et al*, nature nanotechnology 2012.

2. Sage *et al*, nature communications 2015.

3. Sage *et al*, Arxiv 2017.

4. Dominguez-Medina *et al*, Arxiv 2018.

5. Mo Li *et al*, nature nanotechnology 2007.

6. Mile *et al*, nanotechnology 2010.

4:00pm **MN+2D+AN+NS-ThA6 Nonlinear and Noise Induced Dynamics of High Q Nanomechanical Resonators**, *Jana Huber, E.M. Weig*, University of Konstanz, Germany **INVITED**

Doubly-clamped pre-stressed silicon nitride string resonators excel as high Q nanomechanical systems enabling room temperature quality factors of several 100,000 in the 10 MHz eigenfrequency range when operated under vacuum conditions. To retain the high mechanical quality factor, dielectric transduction is implemented as an all-electrical control scheme avoiding the metallization of the string. To this end, the string is exposed to an inhomogeneous electric field created between adjacent electrodes. The resulting gradient field provides an ideal platform for actuation, displacement detection, frequency tuning as well as strong mode coupling between the in- and out-of-plane modes of the string.

Here we focus on the nonlinear dynamics of the string subject to a strong drive. As a result of the high quality factor, cubic as well as higher order nonlinearities are observed. In the presence of thermal fluctuations, satellite resonances arise which enable deep insights into fundamental properties of the system.

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4:40pm **MN+2D+AN+NS-ThA8 A Buckling-based, DC Controlled, Non-volatile Nanoelectromechanical Logic Memory**, *S.O. Erbil, Utku Hatipoğlu*, Bilkent University, Turkey; *C. Yanik*, Sabancı University; *M. Ghavami*, *M.S. Hanay*, Bilkent University, Turkey

Here, we demonstrate a buckling based, nanoelectromechanical logic bit with high controllability and low logic input voltage. The device consists of a slender beam to store information through its buckling direction and a comb-drive structure for initiating buckling electrostatically. When an actuation voltage is applied to the fingers of the comb-drive structure, an axial compressive force is applied to the suspended slender beam which is connected to an anchor from the opposite end. Applied axial force creates a compressive stress on the slender beam which leads to buckling after a critical load. Buckling direction can be controlled (left/right) by changing the applied side-gate control voltages. The capacitive attraction force generated between the beam and the activated electrode controls the direction of the buckling. Control voltage acts as the logic input for writing information and it is only required just before the application of the axial load, so that the beam can be preloaded to the target direction. Lateral deformations as large as 10% of the beam length can be achieved.

Once the beam is buckled to the desired direction, the removal of the guidance voltage does not affect the buckling state of the beam, which indicates successful non-volatile information storage. Moreover, by altering the voltage difference created in the comb-drive structure, buckling amount can be controlled very precisely. Control voltages as low as 0.5V are demonstrated for storing information. The device is fabricated from an SOI wafer by using electron beam lithography, metal deposition and plasma / HF etching techniques. The dimensions of the slender beam are 150nm x 250nm x 40 μ m for the width, thickness and length respectively. Several videos demonstrating dynamically controlled electrostatic buckling have been recorded during the experiments. The nanoelectromechanical logic memory demonstrated here is scalable since its operation does not require any high-end electronic instruments such as function generators, and can be accomplished by simply using DC power sources. To readout the state of the beam all-electronically, the device is capacitively coupled to a microwave resonator. The changes in the frequency shows clear transitions between buckled and straight states.

It is possible to build two-bit mechanical logic gates and more involved logic units by using proposed nanoelectromechanical logic bit. As a further matter, precise control of the buckling in nanoscale can be very promising for demonstrating the interconnection between information science and thermodynamics.

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